

High Current Extraction and Beam Transport - An Introduction -

Ralph Hollinger, GSI

PIBHI Workshop

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High Current Extraction – what I know or believe to know...



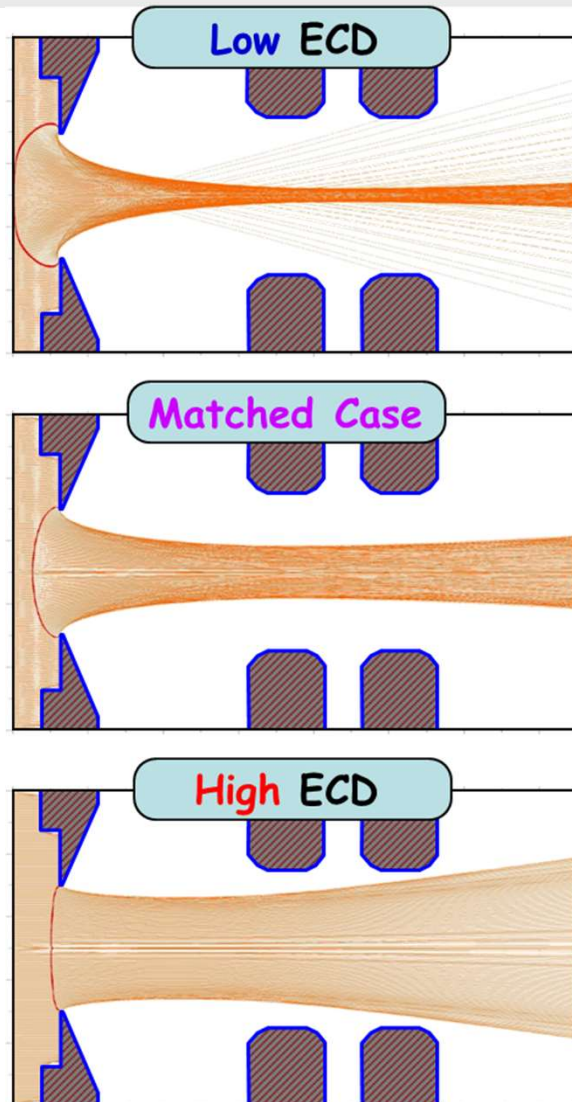
- High Current: 0.1-1 mA, when space charge plays an important role
- Two ways of extraction: space charge limited and emission limited
- Child-Langmuir is valid, I is only a function of r . $S=r/d=0.5$ is optimal, $E_{\max}$ is limited and a function of d . @GSI: $E_{\max}=12\text{kV/mm}$ for 3-4mm
- Kilpatrick and Coupland for $E_{\max}$
- Use triode extraction system with screening electrode; $U_{sc}=10\%$ of U_{ex}
- Emittance is a function of T_i , r and aberrations in the extraction system (no magnetic fields); $\varepsilon_{rms, 89\% \text{ norm.}} = 16r(kT/A)^{0.5}$
- Use pierce geometry ($\sim 70^\circ$) and a thin (0.1mm) edge thickness
- Electrode material: W, Ta, W-Cu (85/15) to increase $E_{\max}$
- For high extr. voltage ($>40\dots 50\text{kV}$) use pentode or post acc. systems
- Switch to multi aperure ext. systems for currents which can not delivered with extrac. hole diameter of max. 8-10mm; emittance growth is the price to pay
- Minimum divergence angle of 20mrad possible; in practice: 40mrad
- H minus is different and Laser ion sources, too
- Simulation: 2d and 3d (with magnetic fields)

High Current Ion Transport – what I know or believe to know...



- High space charge compensation absolutely necessary (>95%)
- No chance to transport a not compensated beam
- You can not avoid scc, electrons everywhere
- Time for scc: 10-30 ns
- scc is more easy for pulsed beams (not chopped), increase of plasma density produces wall electrons by sputtering
- Electrons were generated with residual gas and losses of the beam (sputtering)
- Electrons are trapped inside the beam and can move inside the beam potential: $U = 30 \cdot I / \beta$ (not compensated)
- Beam is compensated also in magnets: QT and bending magnets
- Do not use electrostatic focussing (50s and 60s, nA beam current), use magnets, but only 60% of aperture
- Laser ion beams are different (ns pulse length, no scc, very high dp/p) and H^-
- Solenoids are critical for slow beams (some keV/u) and large beam diameters (>50-60% of aperture) and multi charged beam but good for protons with 100 keV/u or below
- Liouville
- Chopper System

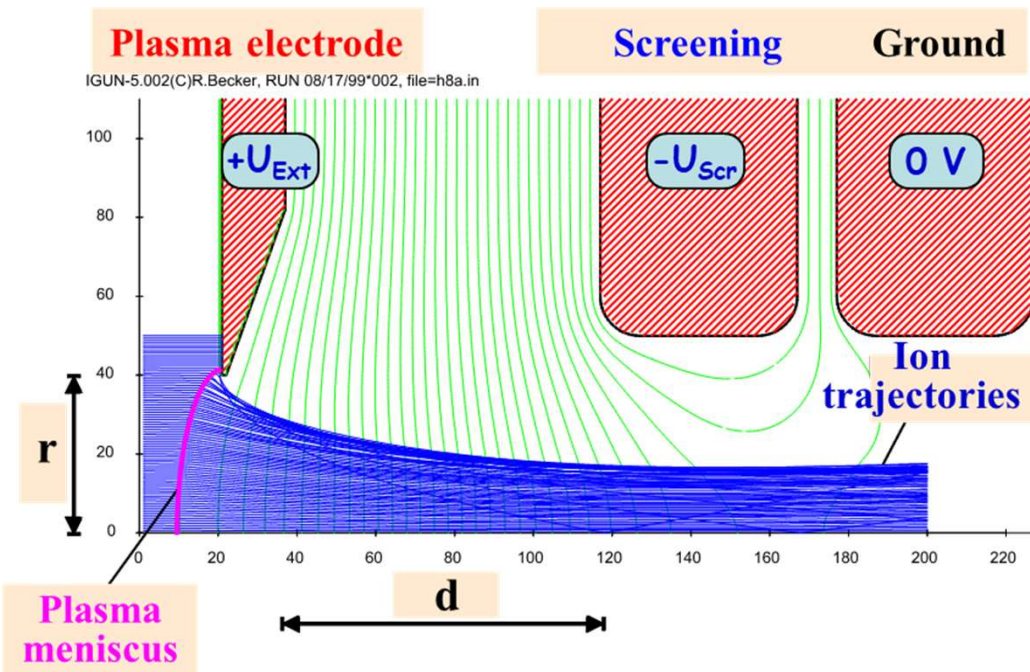
Extraction



Child-Langmuir Law:

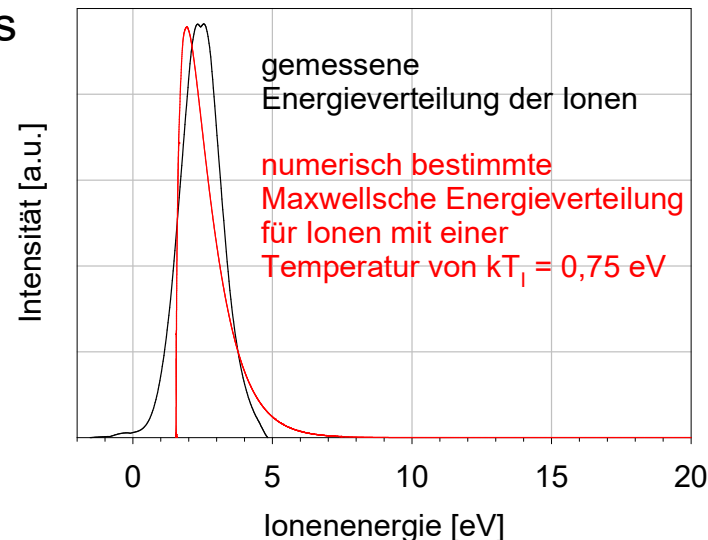
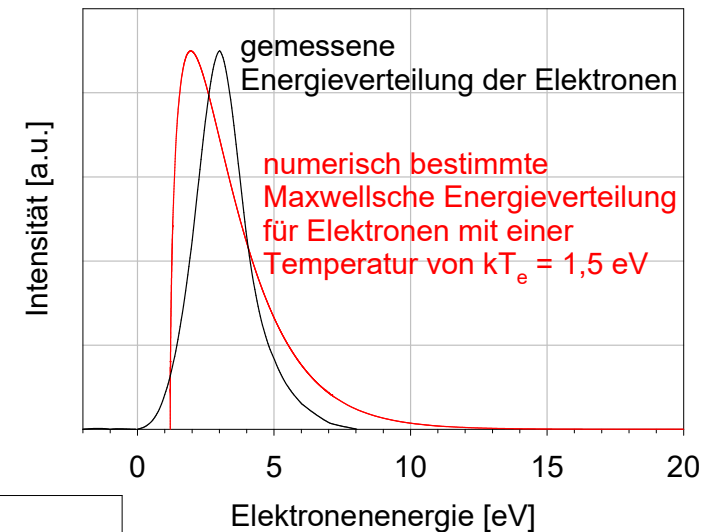
$$j_{CL} = \frac{4}{9} \epsilon_0 \cdot \sqrt{\frac{2e\zeta}{m}} \cdot \frac{1}{\sqrt{d}} \cdot E^{3/2} \quad S = \frac{r}{d} \quad E = \frac{U_{Ext}}{d}$$

$$I_{CL} = \frac{4}{9} \pi \cdot \epsilon_0 \cdot \sqrt{\frac{2e\zeta}{m}} \cdot S^2 \cdot U_{Ext}^{3/2}$$



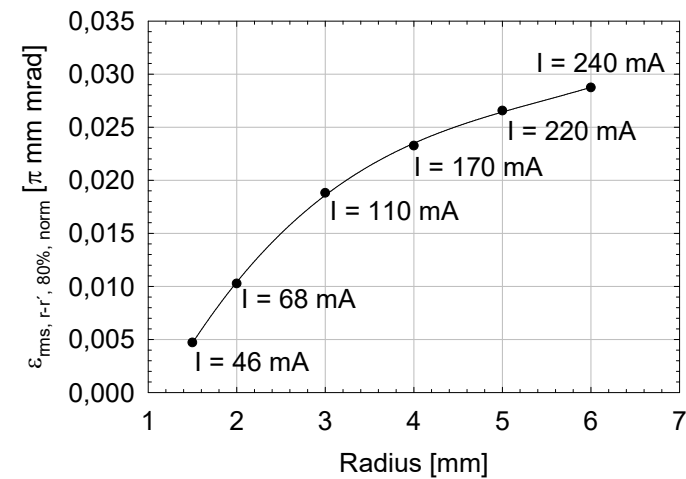
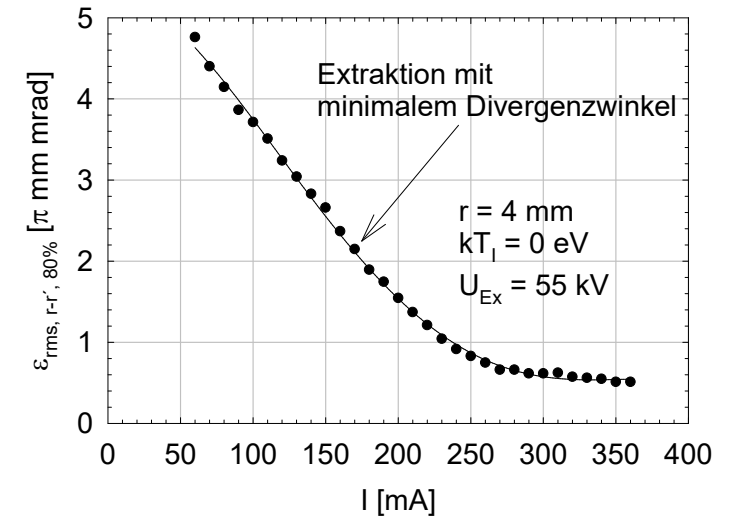
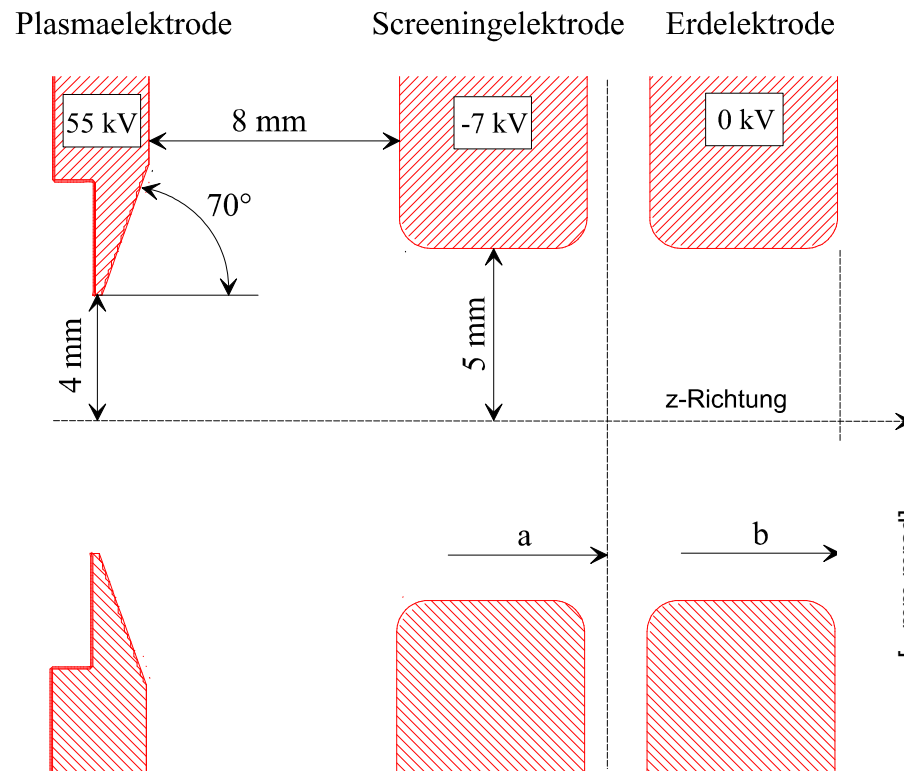
Plasma Parameter

- Particle density: n_i , n_e , N
- Particle: temperature: T_i , T_e
- Particle energy: E_i , E_e
- Plasma wall Potential: U_{PW}
- Charge state distribution
- Ion mass
- Magnetic fields
- Electric Fields
- Geometry
- Residual gas particles
- ...

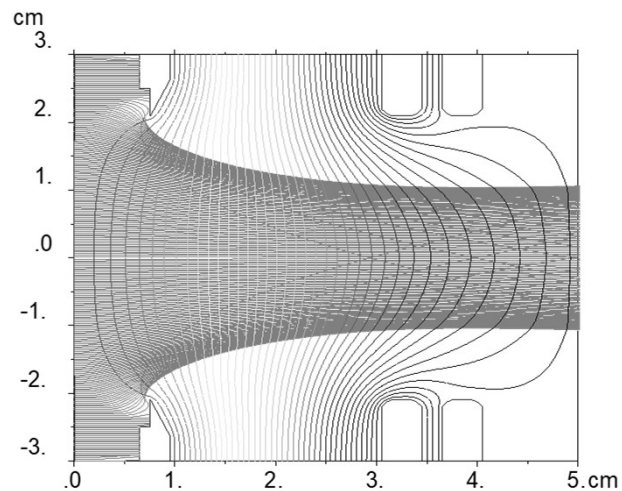


Extraction System

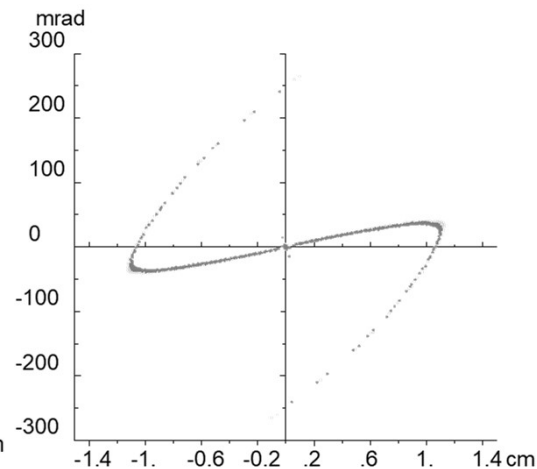
$$\varepsilon_{rms, 89\%, norm} = 16,325r \sqrt{\frac{kT}{A}}$$



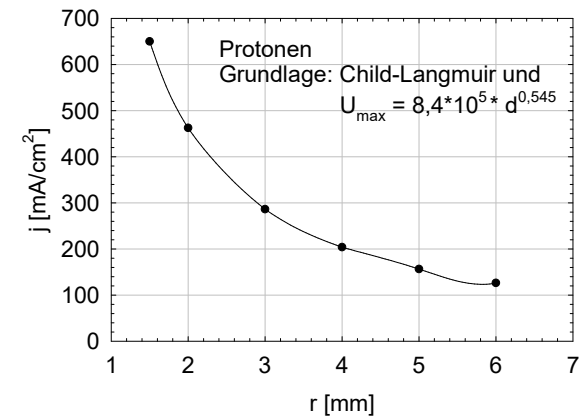
Multi Aperture Extraction System – why?



AXCEL-INP simulation for extraction of 35 mA Bi^+ and 8.75 mA Bi^{2+} with a single aperture extraction system



Emittance pattern of the trajectory plot of Figure 5.19 ($\epsilon_{100\%} = 3000 \pi \text{ mm mrad}$, $\epsilon_{\text{rms}} = 367 \pi \text{ mm mrad}$)

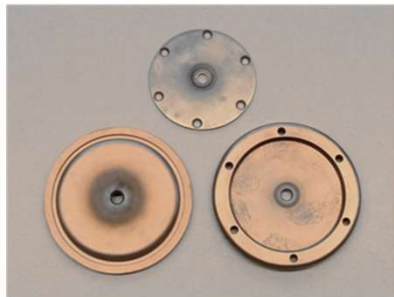


Multi Aperture Extraction System



Triode Extraction Systems:

1 hole
 $\varnothing 4 \div 8$ mm



7 holes
 $\varnothing 4 \div 6$ mm



13 holes
 $\varnothing 3$ mm



19 holes
 $\varnothing 2 \div 3$ mm



Plasma - Screening
distance:

$r = 3$ mm

Aspect Ratio:

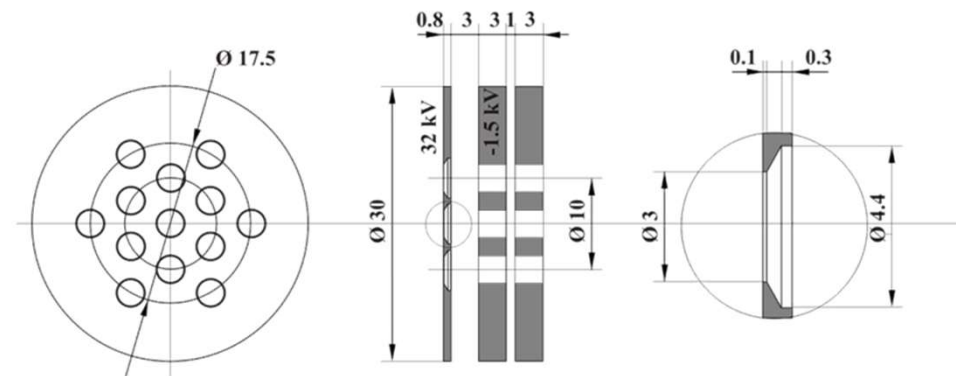
$S = 0.5$

MAX Ext. Voltage:

35 kV

Emission Area:

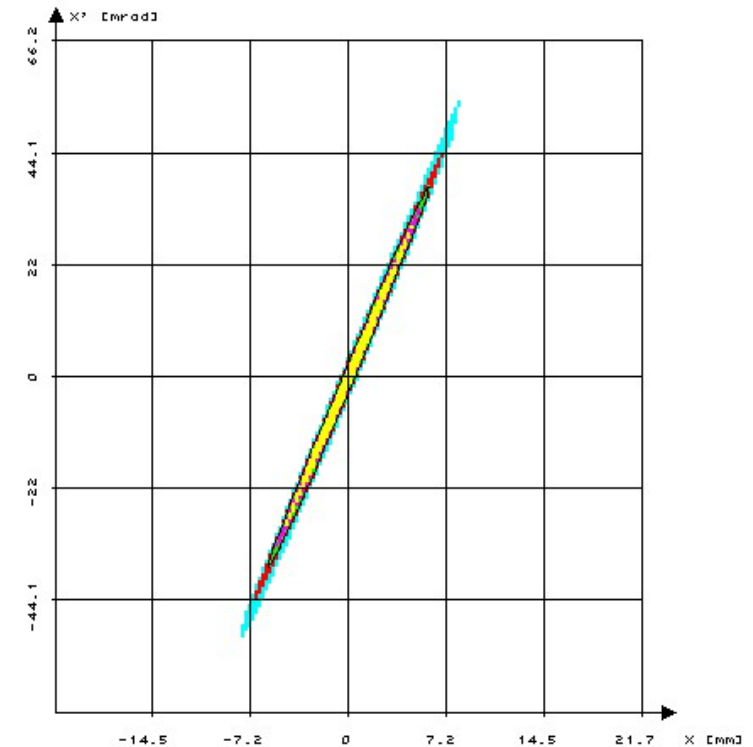
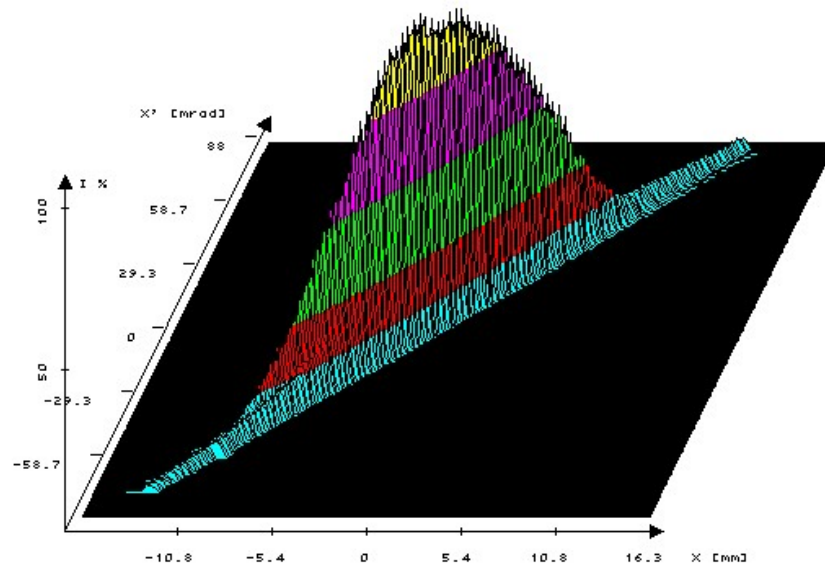
92 mm²



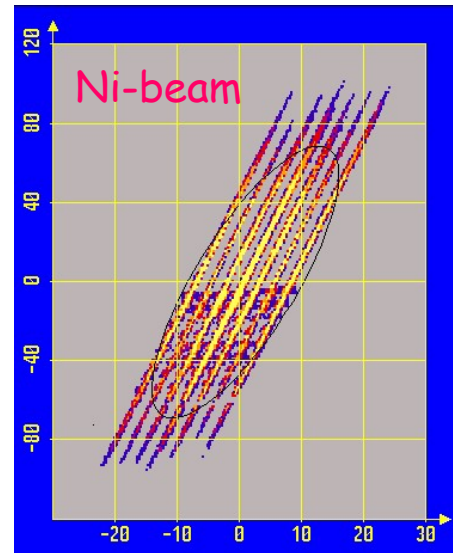
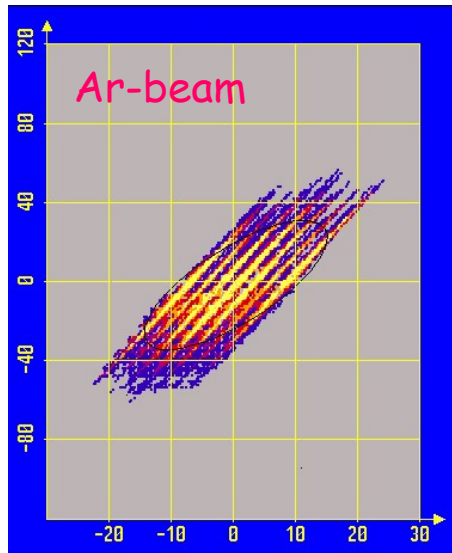
56mA Protons @ 26kV

(85 % H⁺, 56 mA, 26 keV)

Divergence angle (80 %)	38 mrad
Beam radius (80 %)	5,9 mm
ε (x-x', 80 %)	$6,3\pi$ mm mrad
ε (rms, x-x', 80 %)	$4,55\pi$ mm mrad
ε (rms, x-x', 89 %)	$5,66\pi$ mm mrad
ε (rms, x-x', 80 %, norm.)	$0,034\pi$ mm mrad
ε (rms, x-x', 89 %, norm.)	$0,042\pi$ mm mrad
ε (rms, x-x', 100 %, norm.)	$0,062\pi$ mm mrad



Filament vs. Vacuum Arc Ion Source

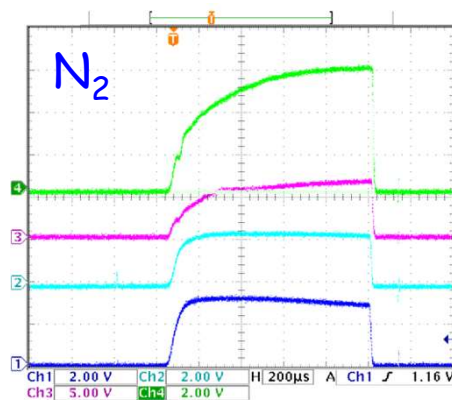


Beam Characteristics

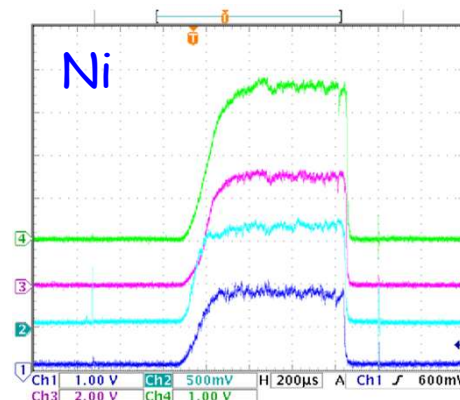
Ar-beam Ni-beam
(CHORDIS) (VARIS)

U_{Exr} :	18 kV	18 kV
I_{Ext} :	60 mA	60 mA
Div. Angle:	50 mrad	95 mrad

CHORDIS



VARIS

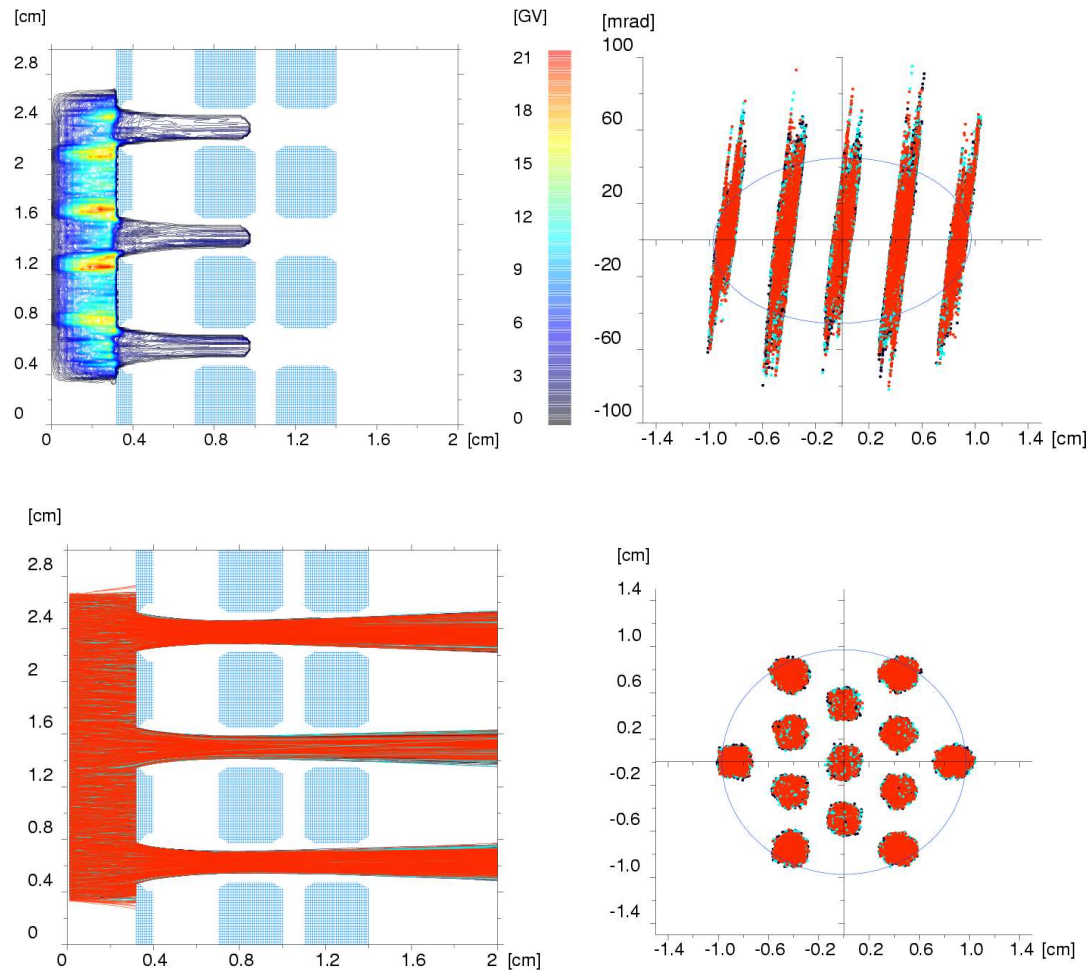


Ion beam pulses along the LEBT

N_2 -beam Ni-beam
(CHORDIS) (VARIS)

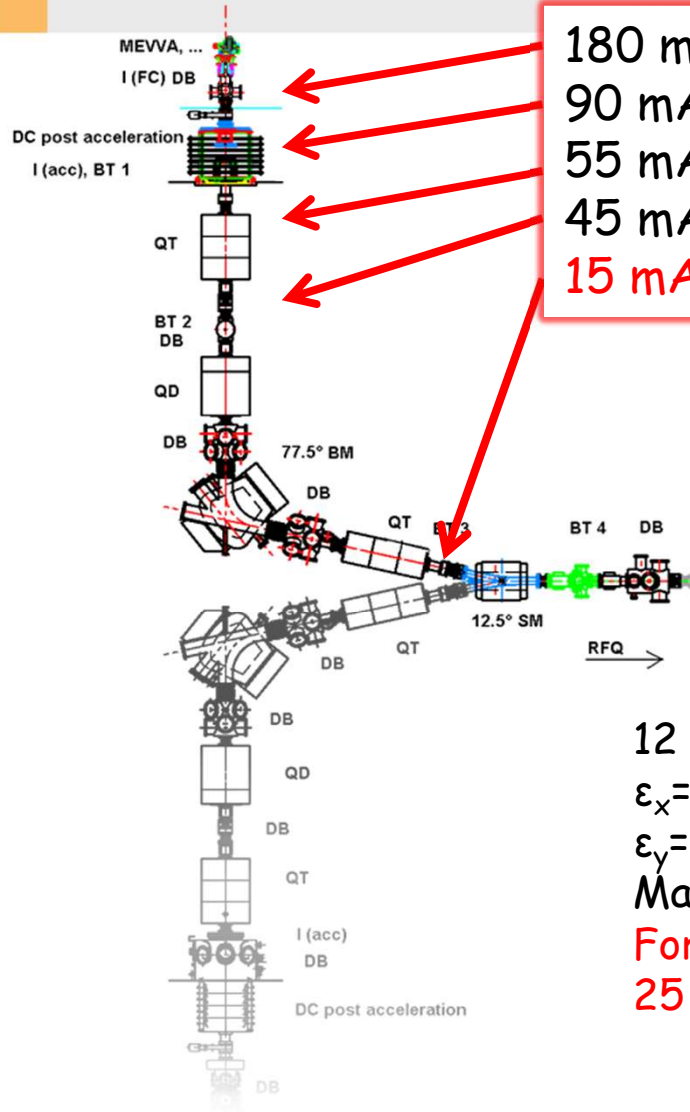
CT 1:	20 mA/div	10 mA/div
CT 2:	20 mA/div	5 mA/div
CT 3:	5 mA/div	2 mA/div
CT 4:	2 mA/div	1 mA/div

KOBRA3D-Simulation



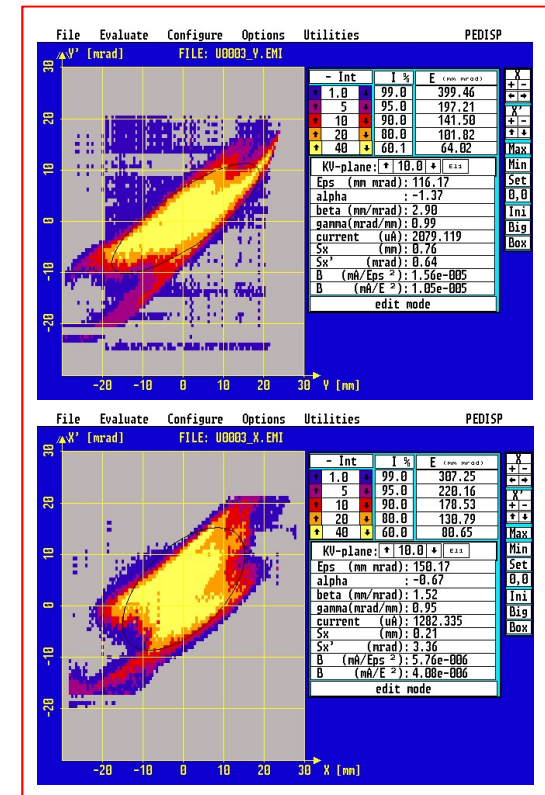
Ion fraction	$U^{3+} = 16 \%$, $U^{4+} = 67 \%$ $U^{5+} = 14 \%$, $U^{6+} = 3 \%$
Potential plasma electrode	32 kV
Potential screening electrode	-1.5 kV
Emission current density for standard operation	150 mA/cm ²
Longitudinal ion energy	160 eV
Transversal ion energy*	100 eV
Ion temperature	5 eV
Plasma potential hump	10 V
Electron temperature	10 eV
Potential hump for electrons**	-10 eV
Number of meshes x, y, z	151, 151, 201
Number of trajectories	250000

High Current LEBT

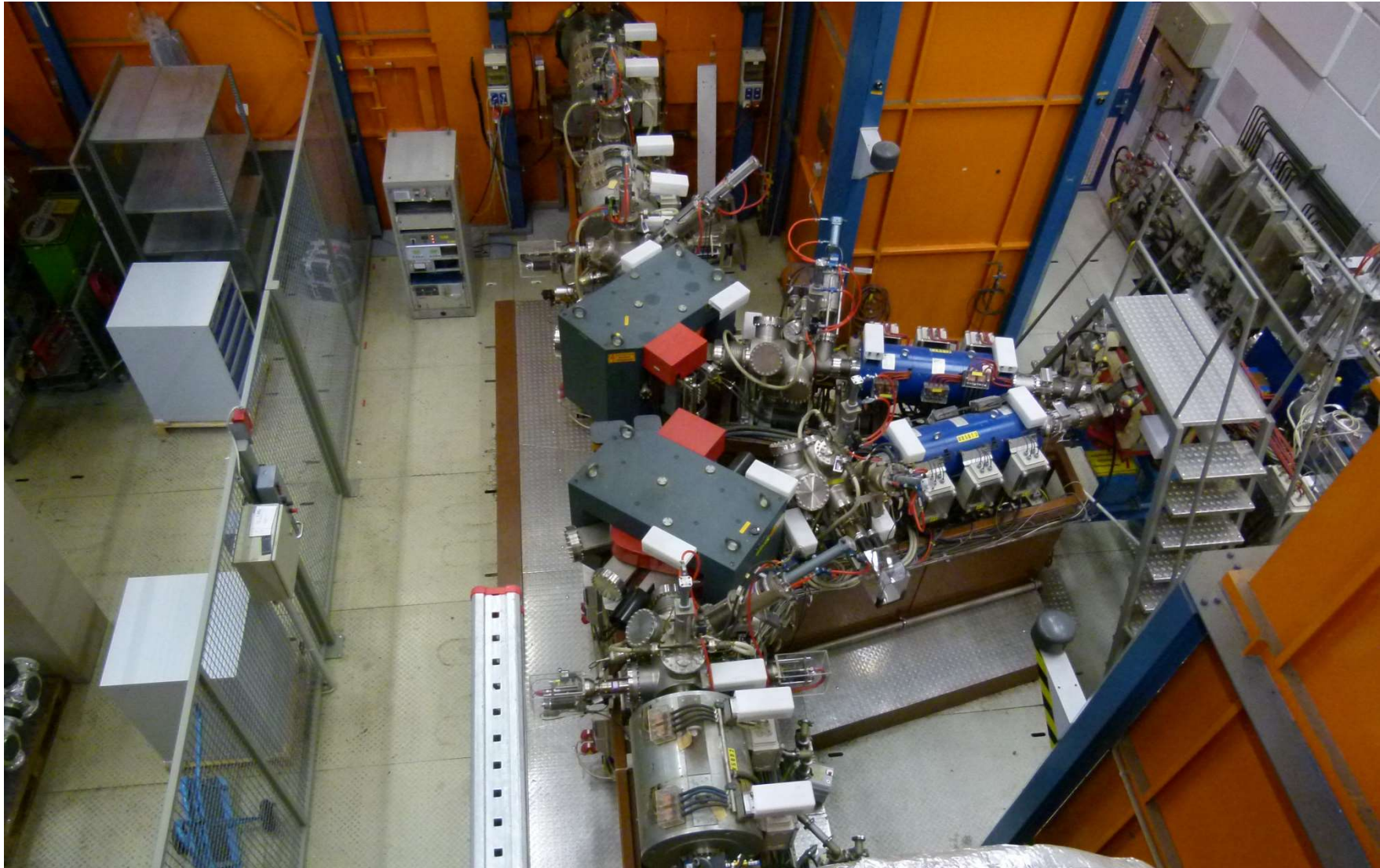


180 mA, 120 mA U^{4+}
 90 mA, 60 mA U^{4+}
 55 mA, 37 mA U^{4+}
 45 mA, 30 mA U^{4+}
 15 mA U^{4+} , Max.: 25 mA

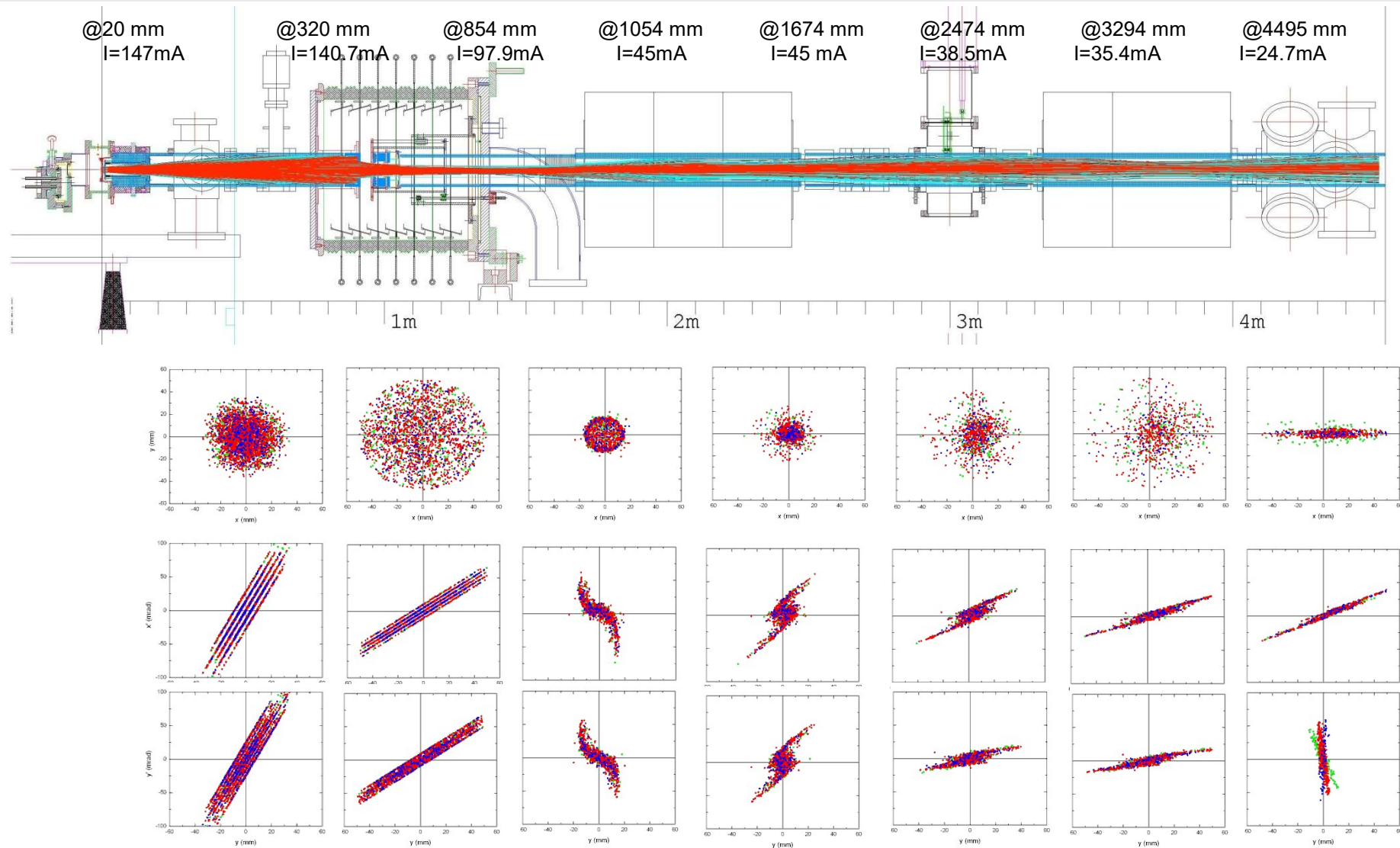
12 mA U^{4+} (in front of RFQ)
 $\epsilon_x = 220\pi$ mm mrad
 $\epsilon_y = 200\pi$ mm mrad
 Max.: 16 mA
 For FAIR:
 25 mA, $\epsilon_x = 250\pi$ mm mrad



High Current LEBT



KOBRA3D-Simulation



SCC is Important !



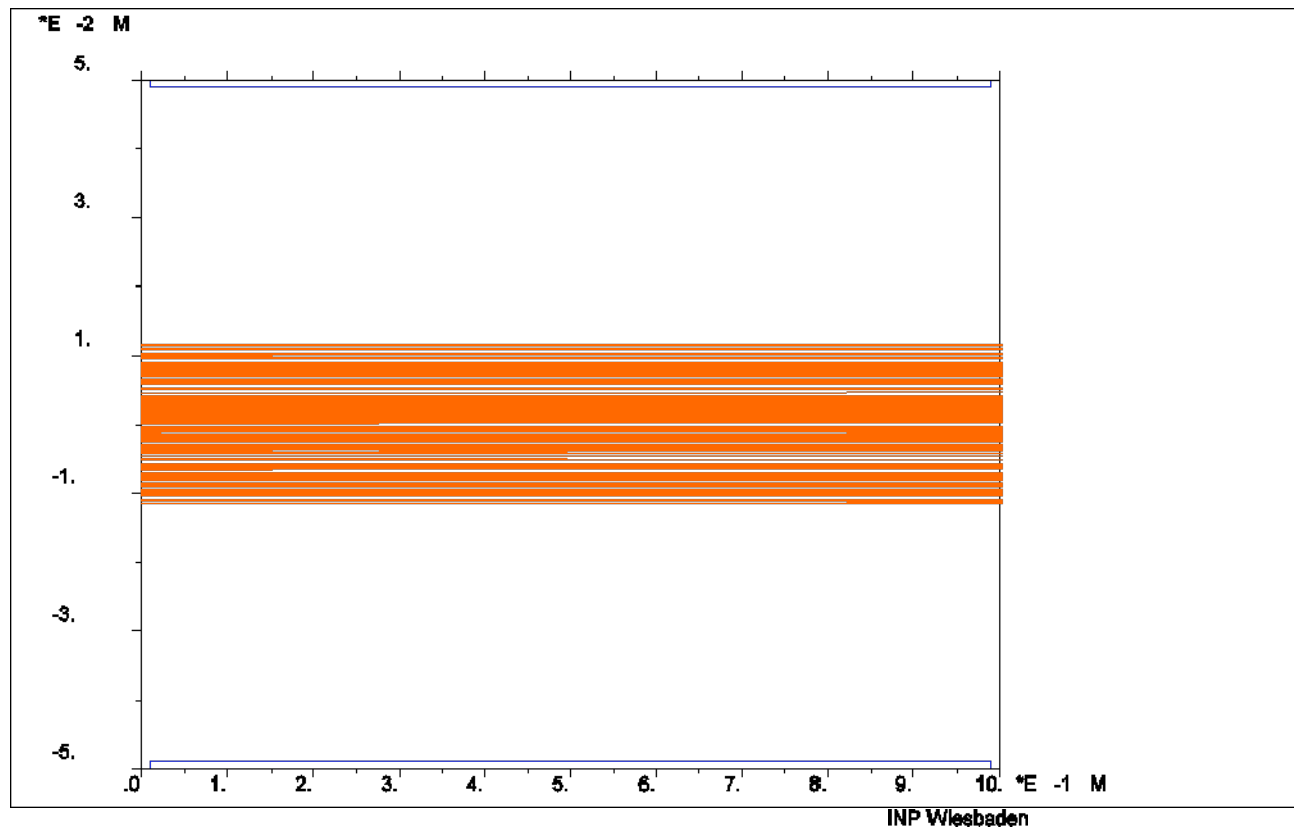
AXCEL-INP VERSION

4.36

2D plot

ITERATION

1



COMMENT: drifting beam 30 keV, 100mA

DATE: 06/01/03

TIME: 22:38:30

SCC is Important !



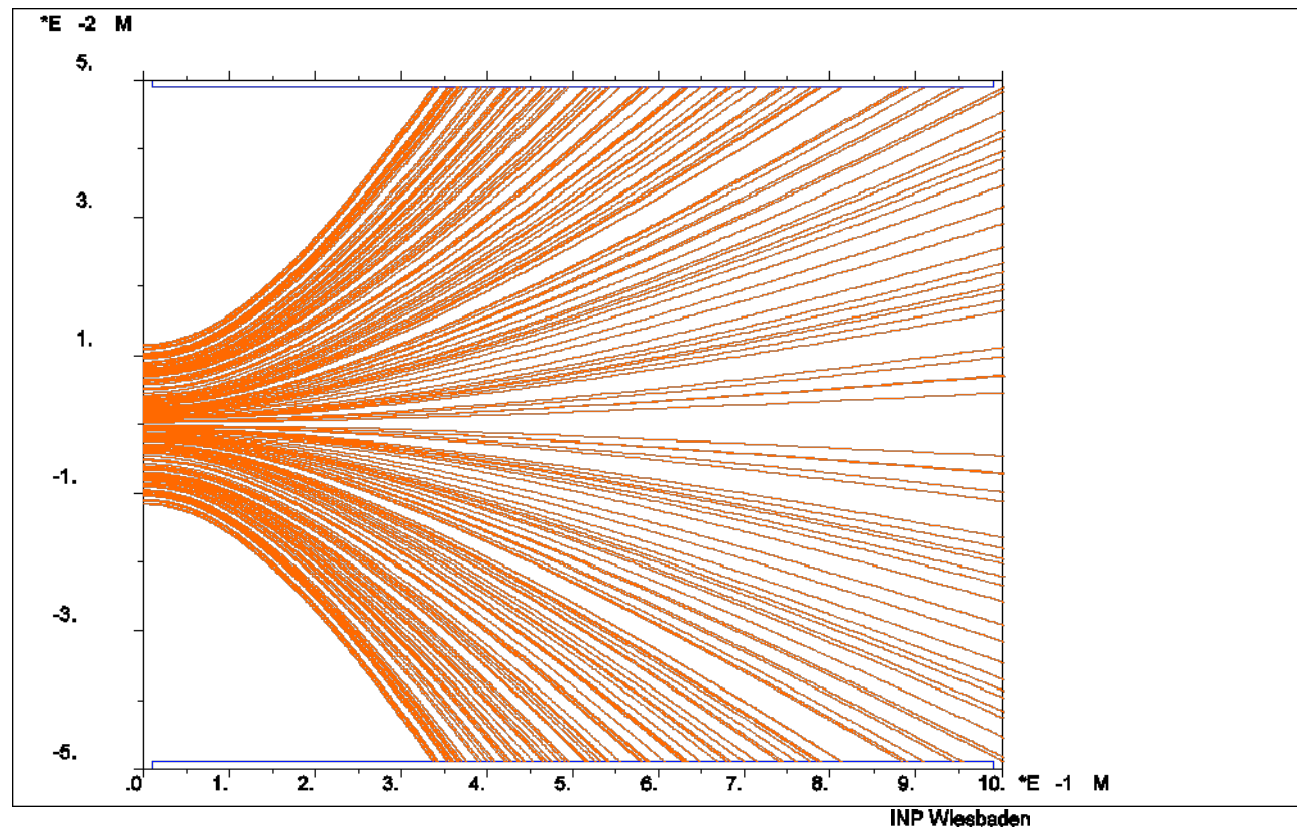
AXCEL-INP VERSION

4.36

2D plot

ITERATION

8

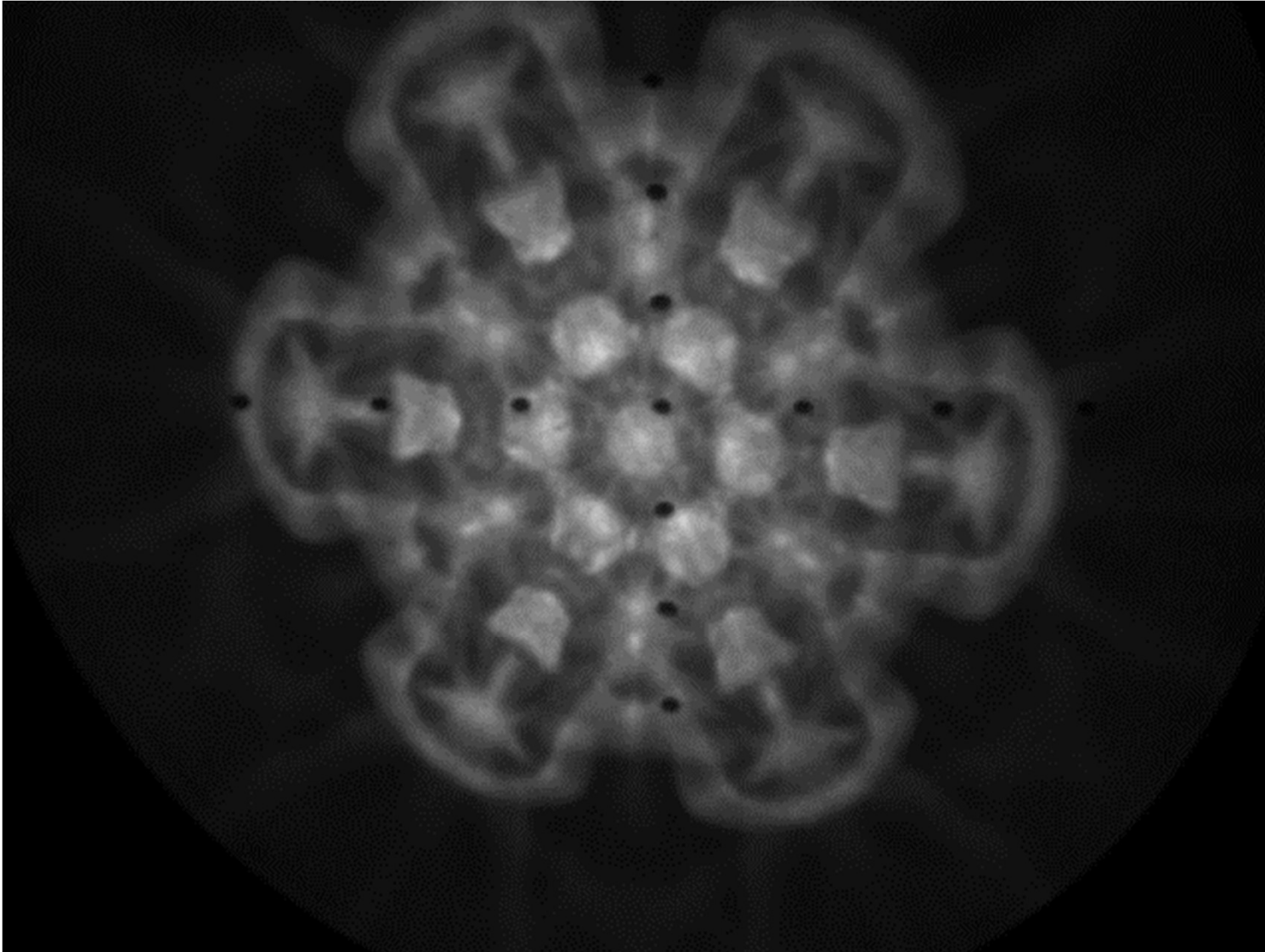


COMMENT: drifting beam 30 keV, 100mA

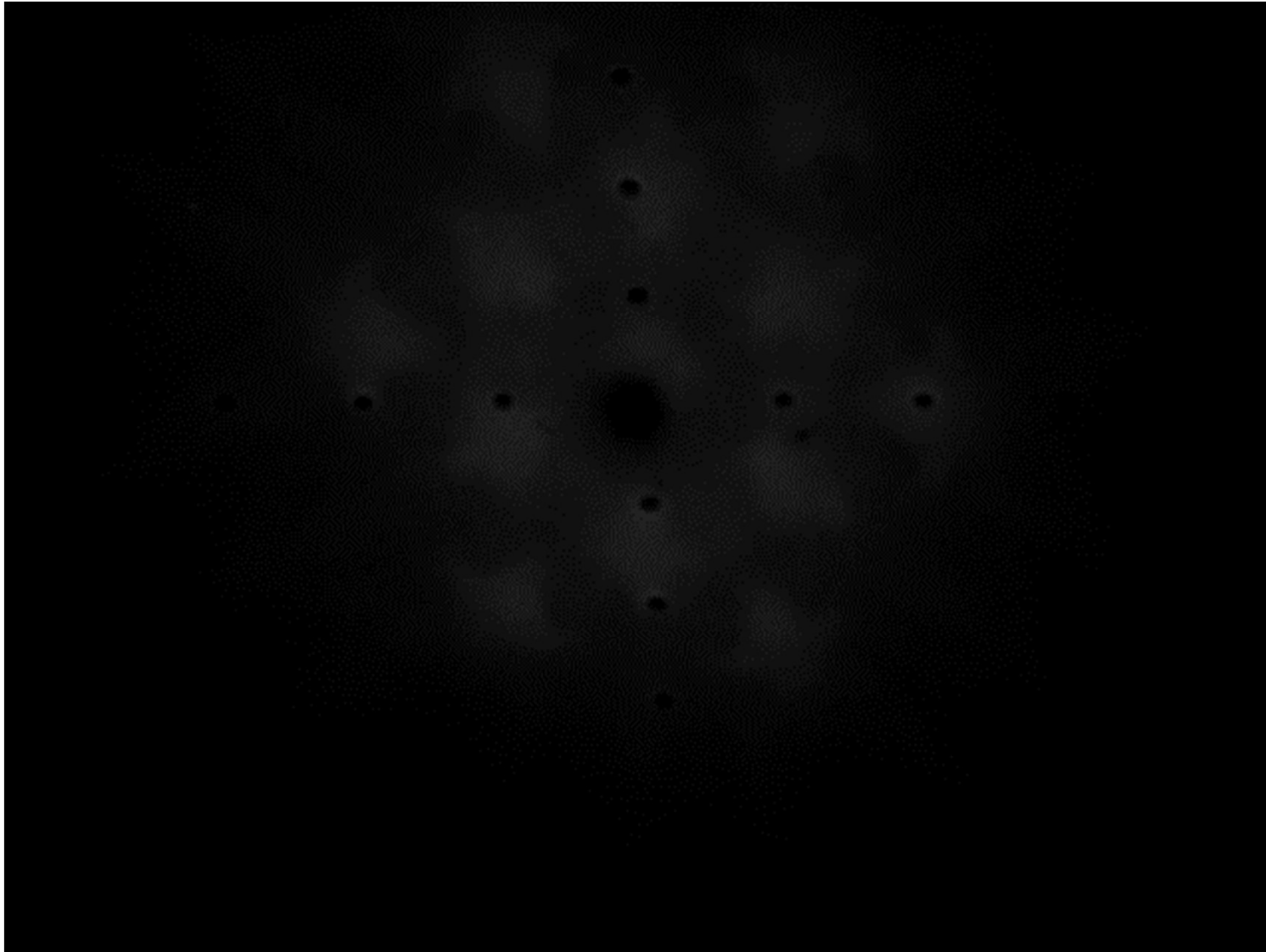
DATE: 06/01/03

TIME: 23:02:39

Video Solenoid



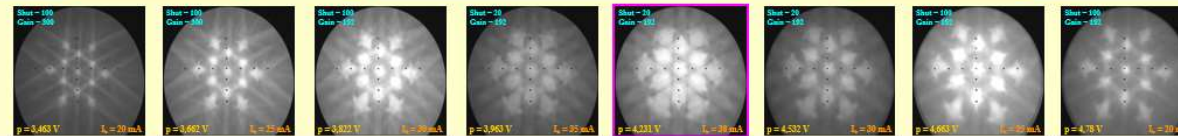
Video Solenoid



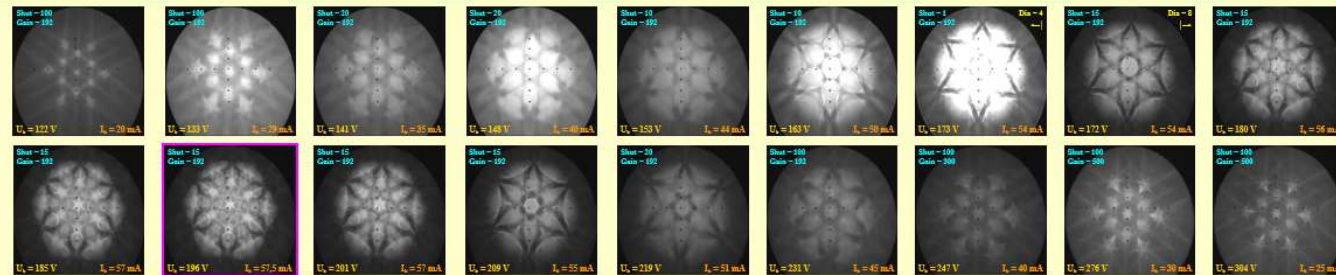
Solenoids

He beam with Viewing Target

Gas Pressure:



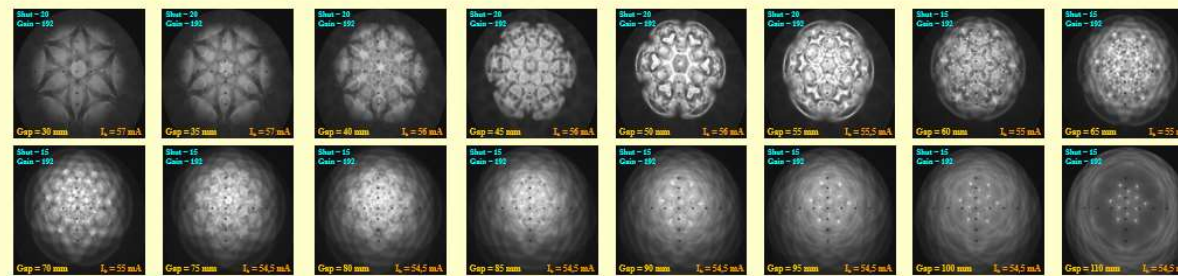
Arc Voltage:



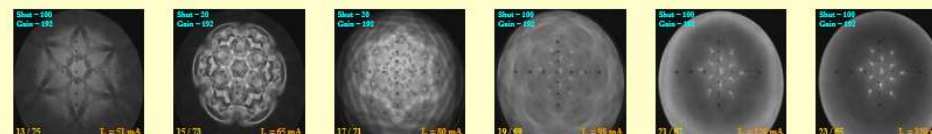
Fillament Current:



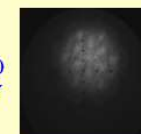
Gap Width:



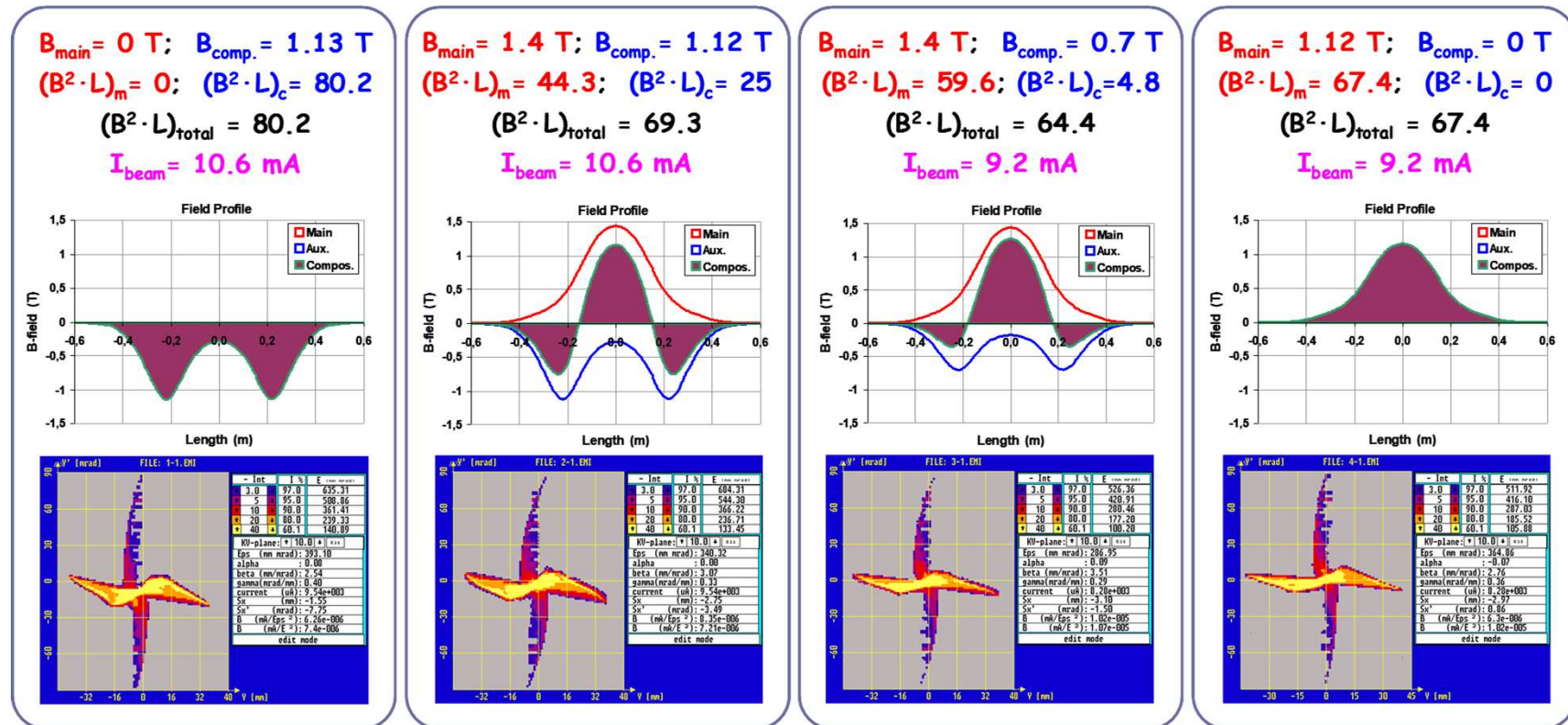
$U_{\text{ext}} / U_{\text{PA}}$: (MAX I_{beam})



Ghosts
(strong sparking)
when $U_b > 350 \text{ V}$



Influence of the Field Profile on the Beam Emittance

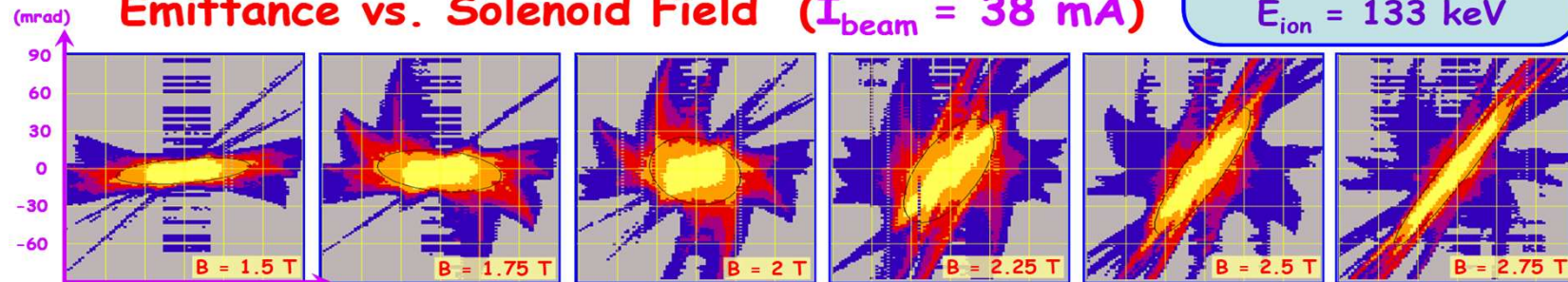


Solenoids

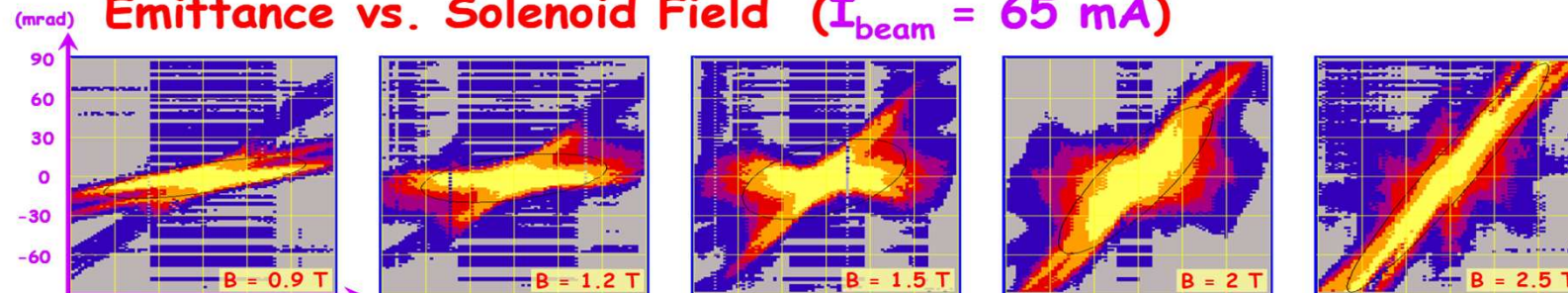
$^{181}\text{Ta}^{3+}$ (MEVVA)

$E_{\text{ion}} = 133 \text{ keV}$

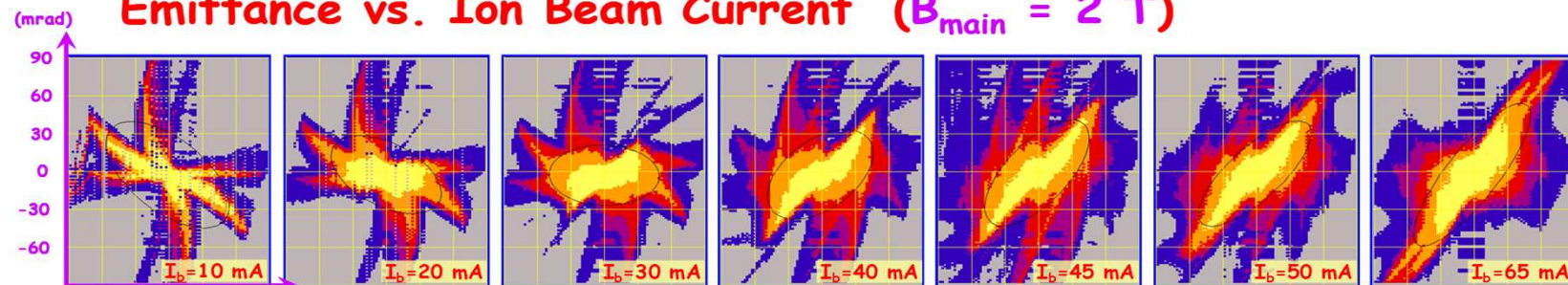
Emittance vs. Solenoid Field ($I_{\text{beam}} = 38 \text{ mA}$)



Emittance vs. Solenoid Field ($I_{\text{beam}} = 65 \text{ mA}$)



Emittance vs. Ion Beam Current ($B_{\text{main}} = 2 \text{ T}$)



Experimental Setup



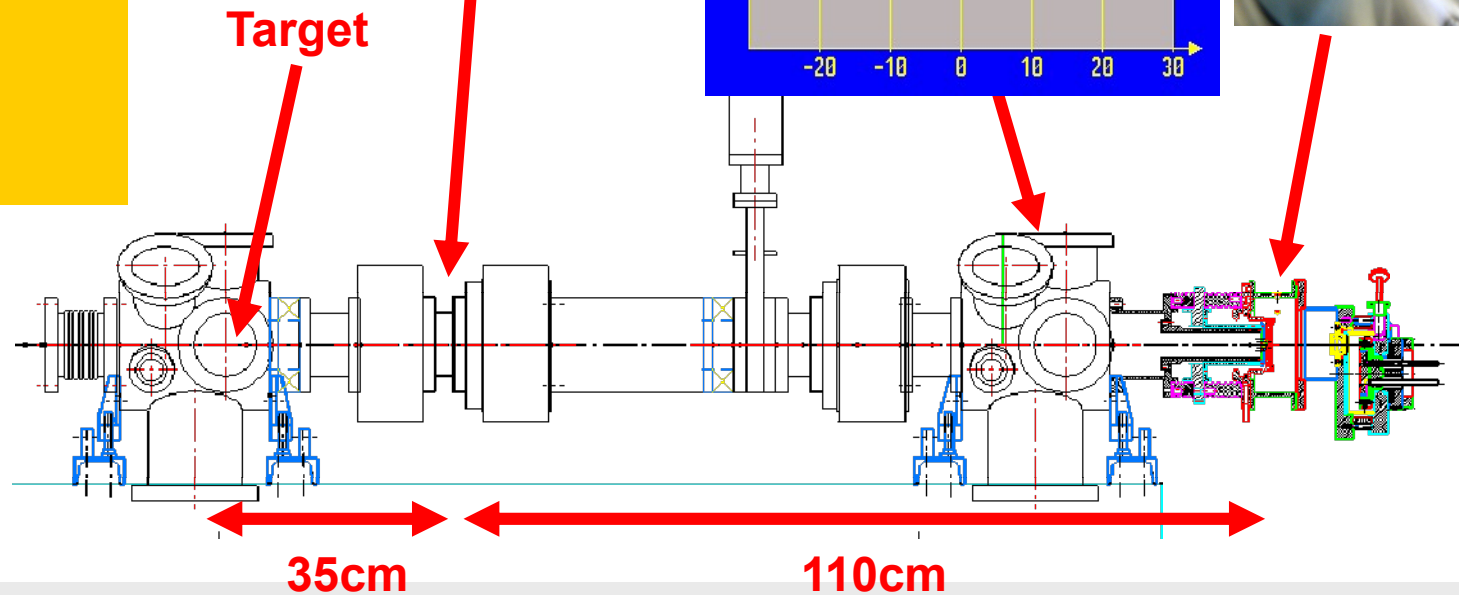
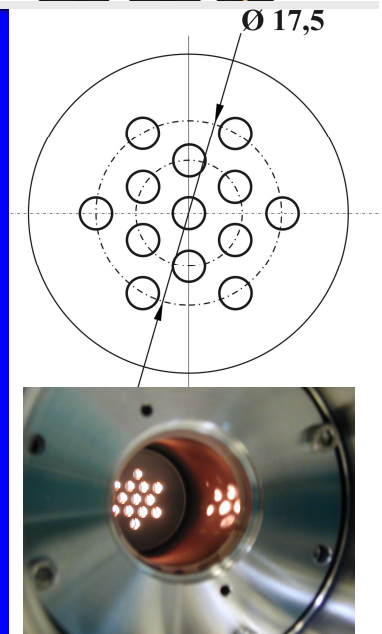
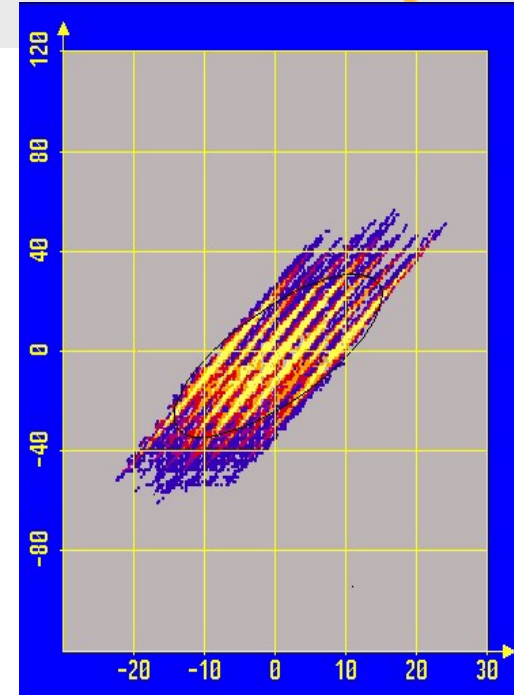
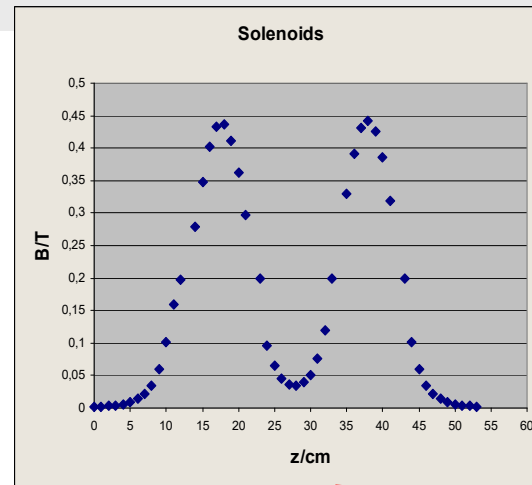
Ion Source:
CHORDIS

Ions:
98% He⁺
2% He²⁺

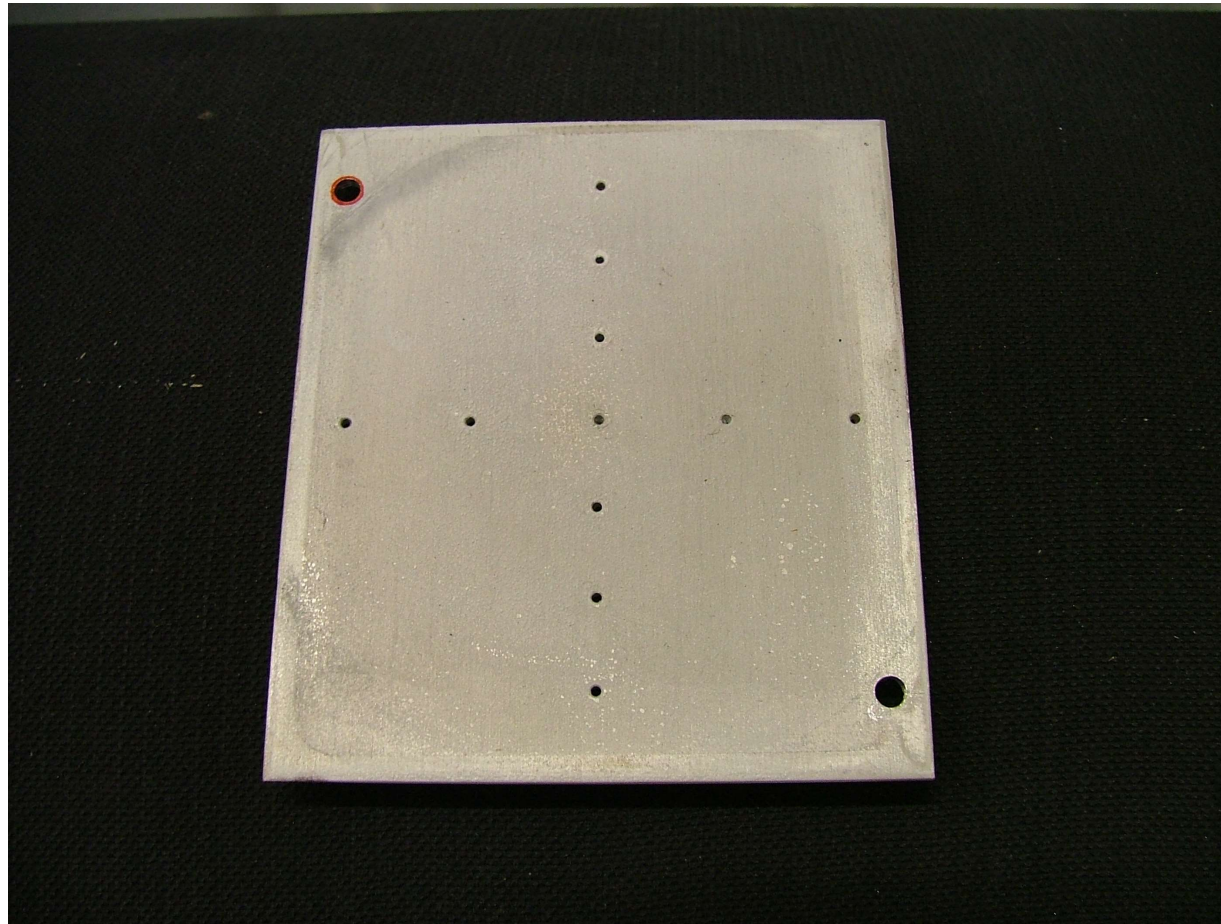
Ion Current:
60mA@22kV

Extraction System:
13 x 3mm

Viewing Targets:
YO₂S
KBr
BaF

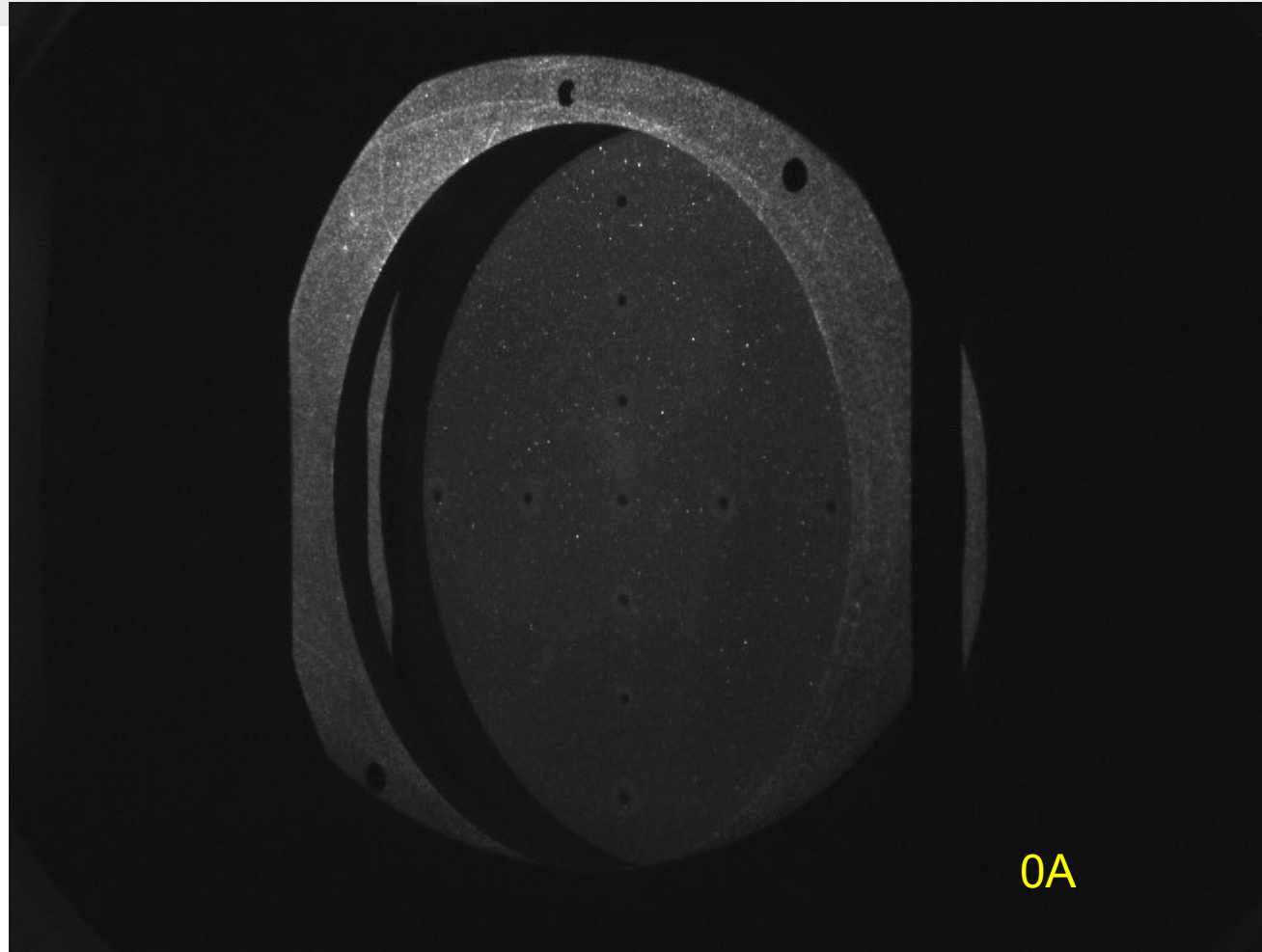


Viewing Target



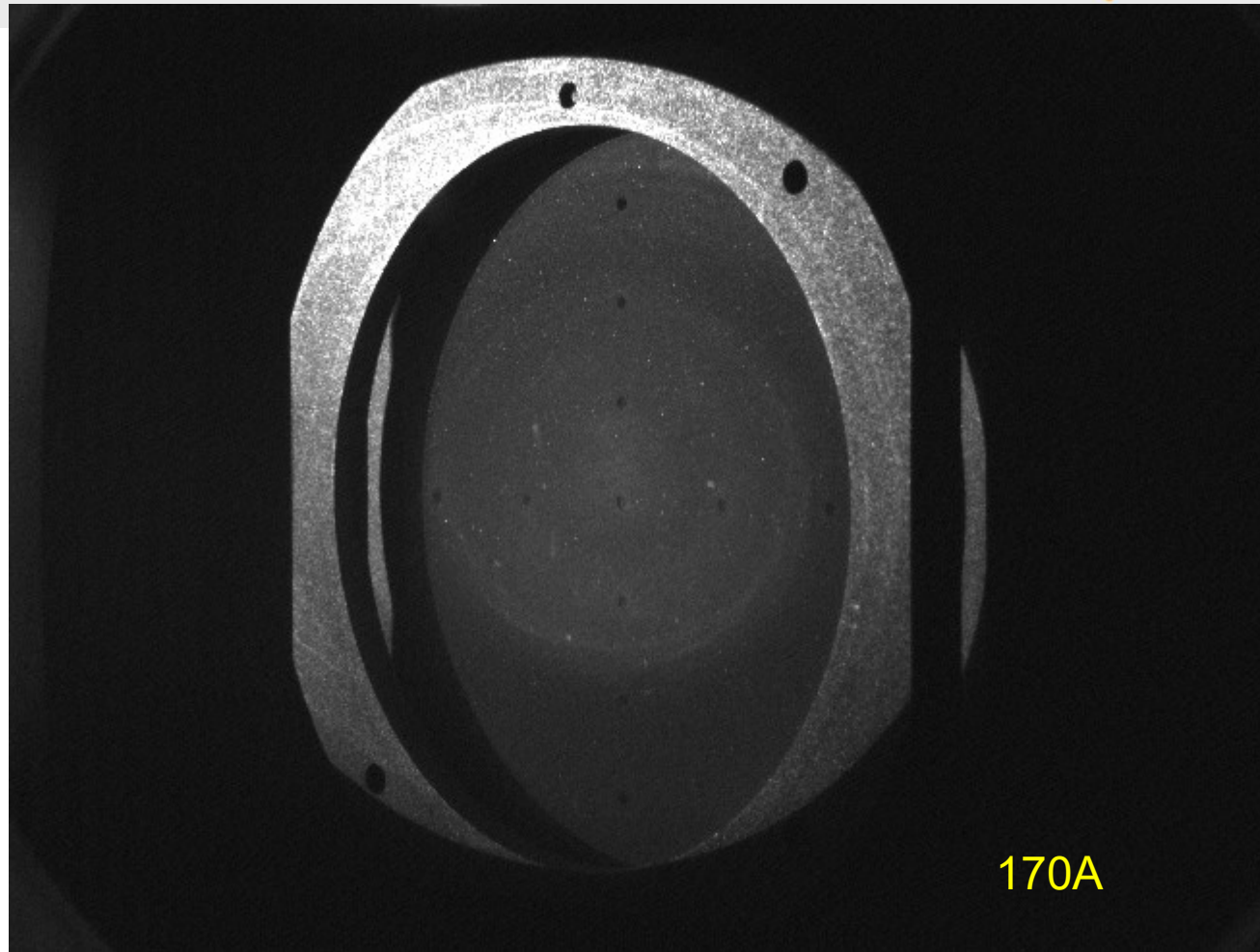
Viewing Target (YO_2S), no Impurities, High Curr.

FAIR GSI



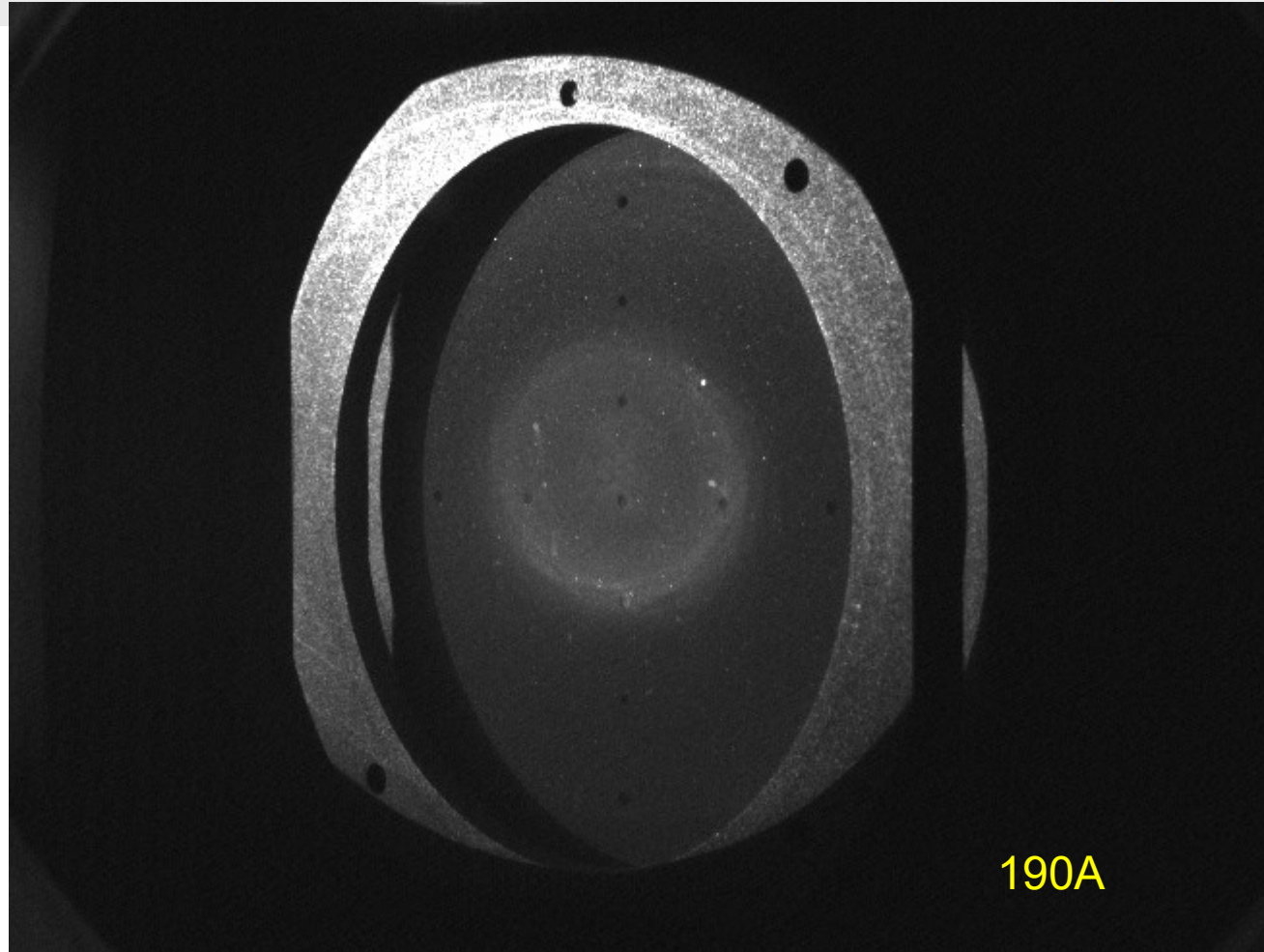
0A

Viewing Target



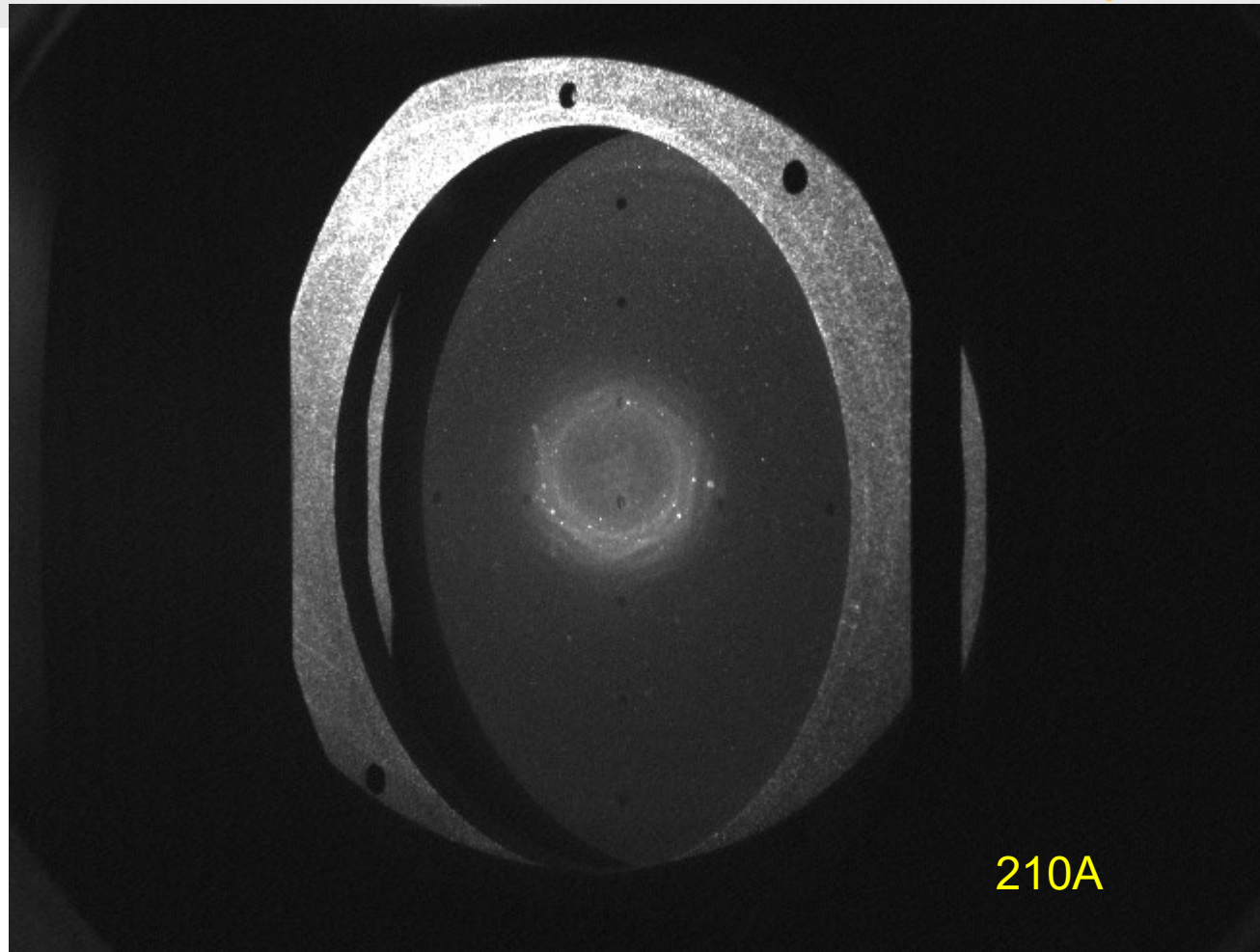
170A

Viewing Target

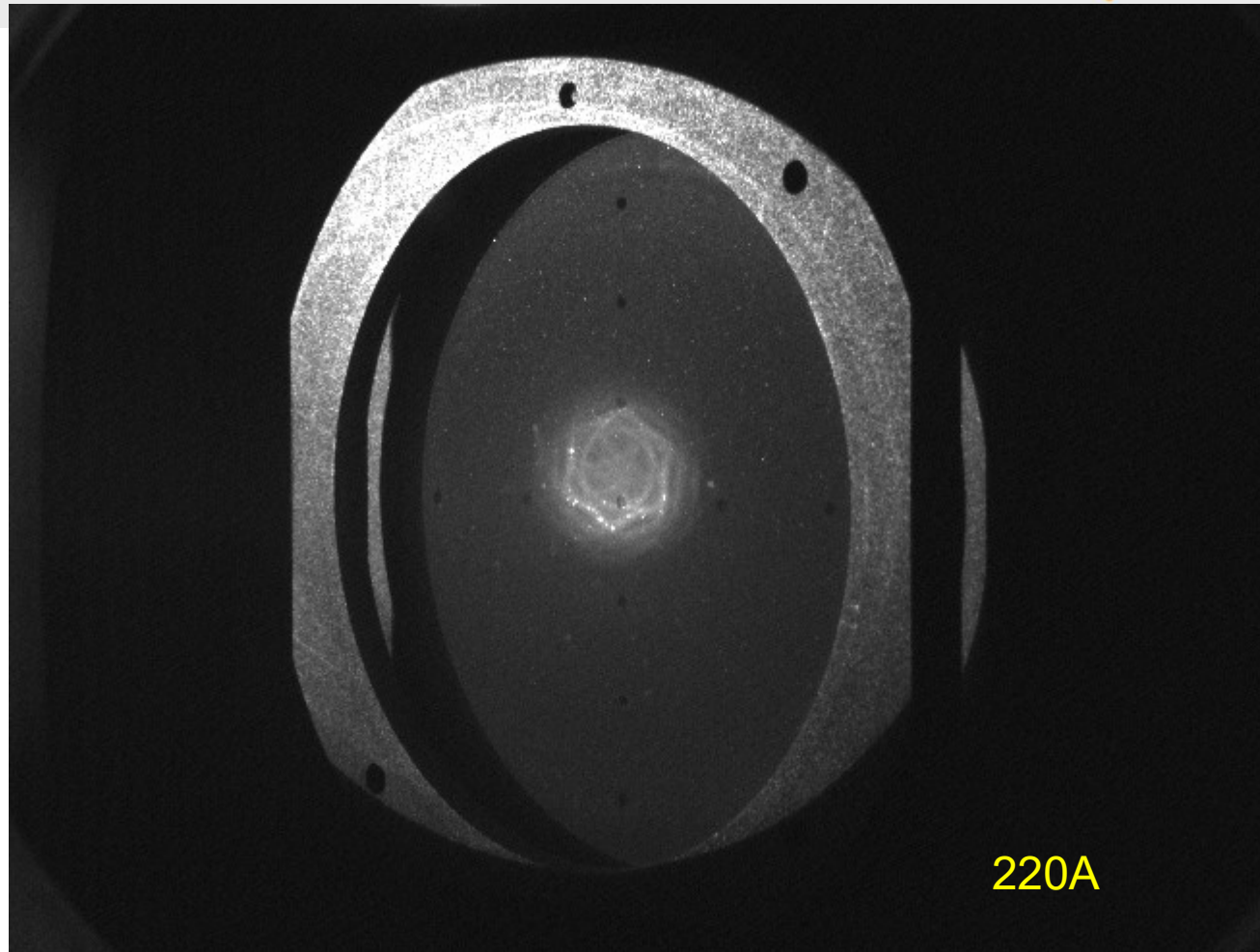


190A

Viewing Target

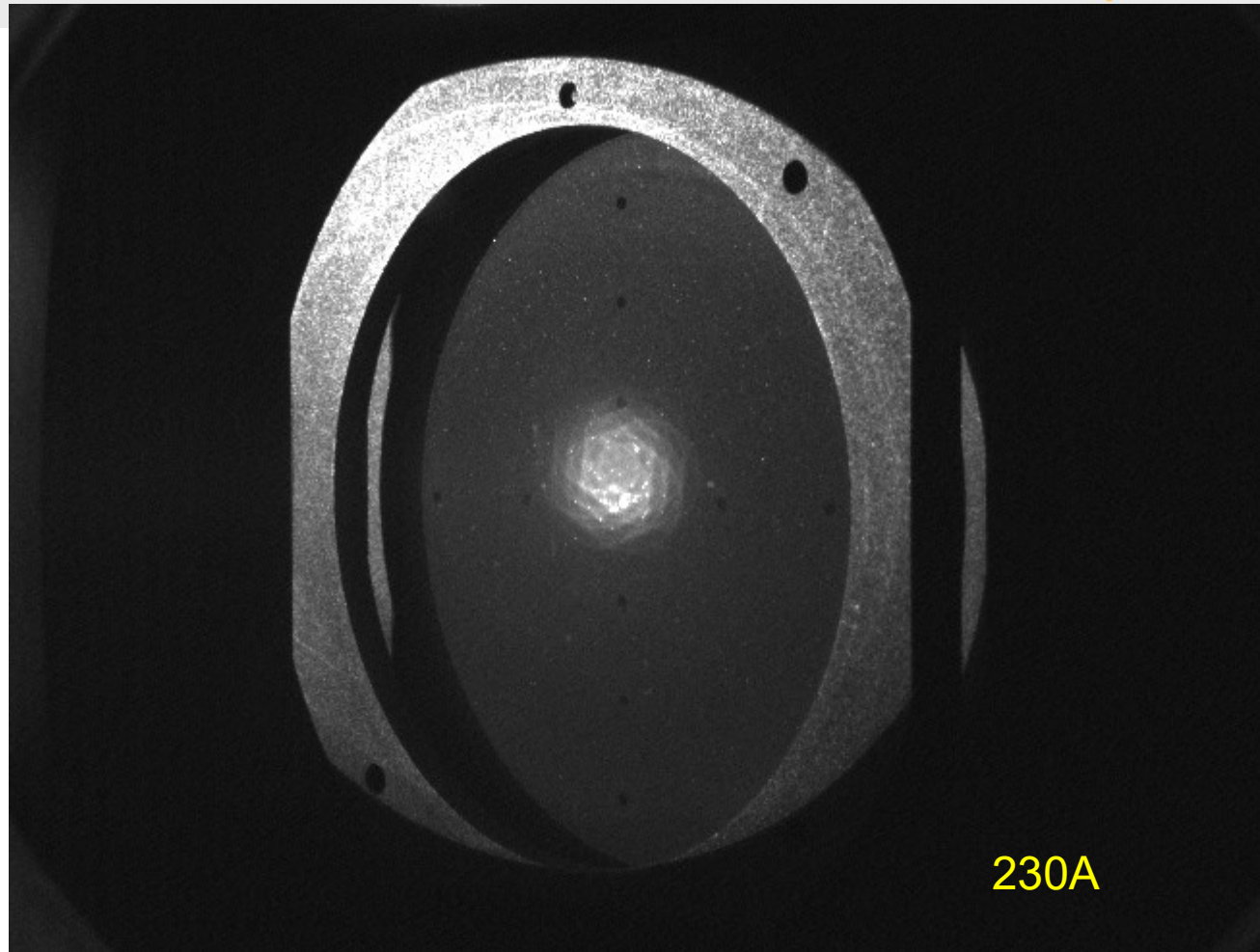


Viewing Target



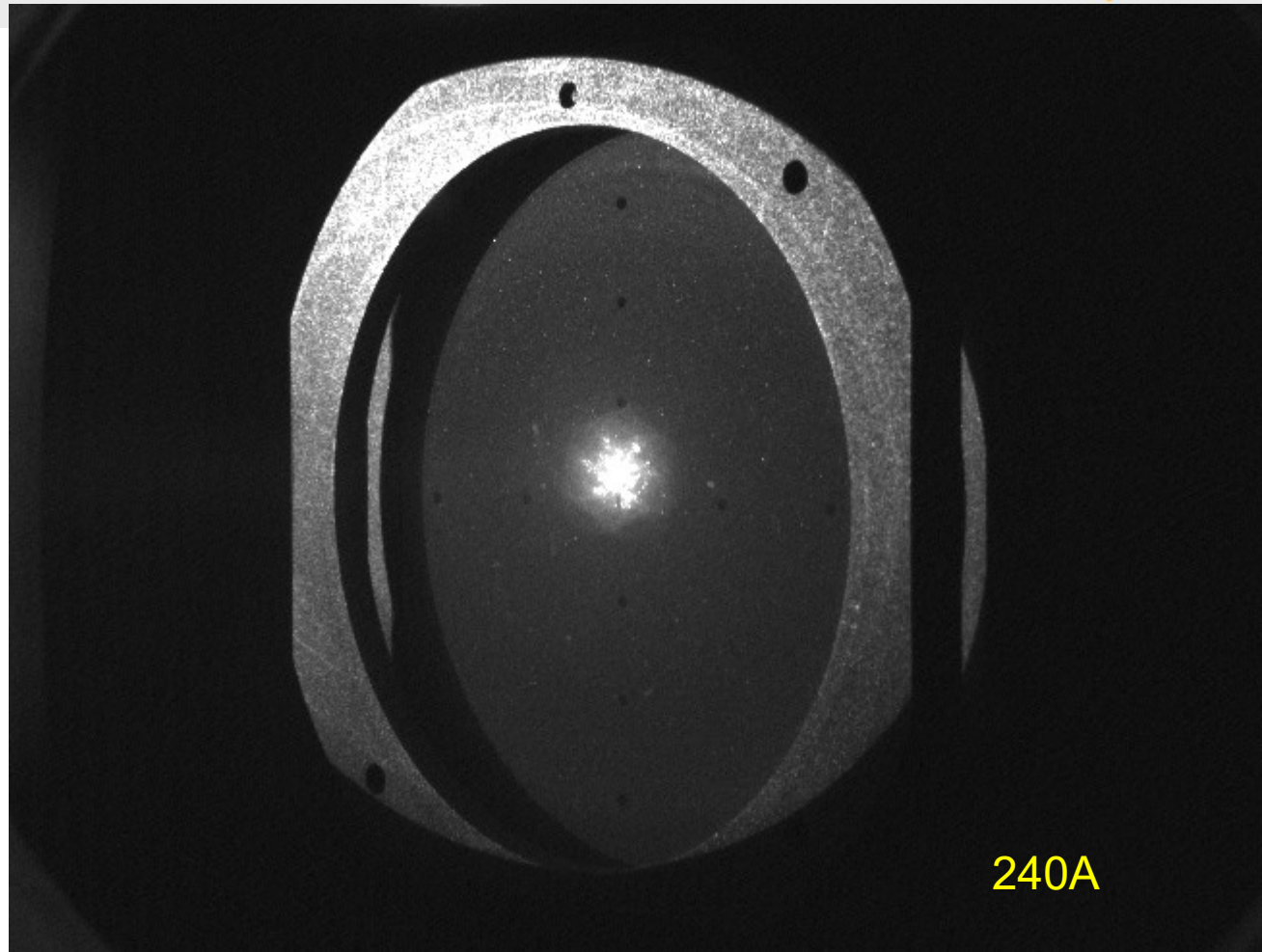
220A

Viewing Target



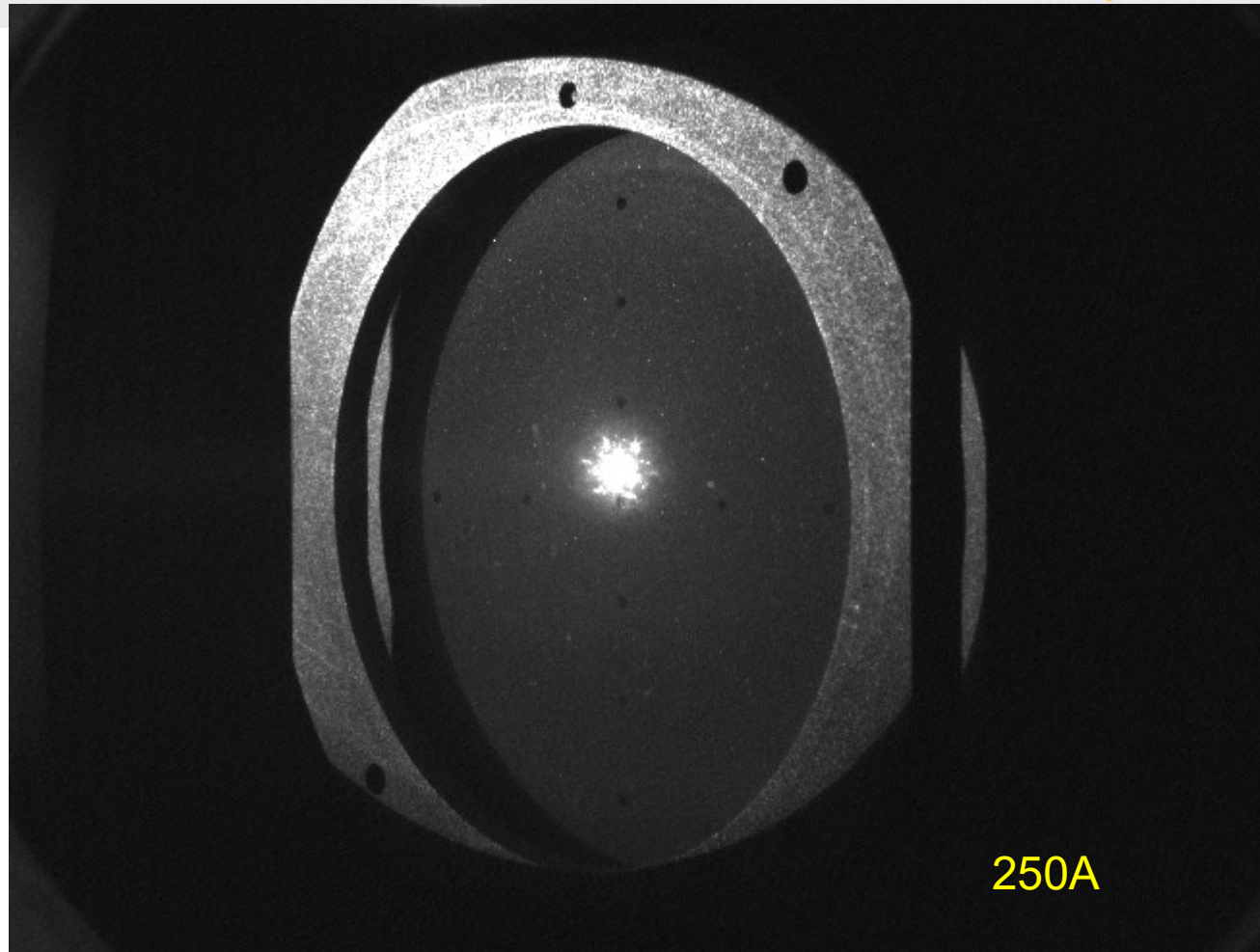
230A

Viewing Target



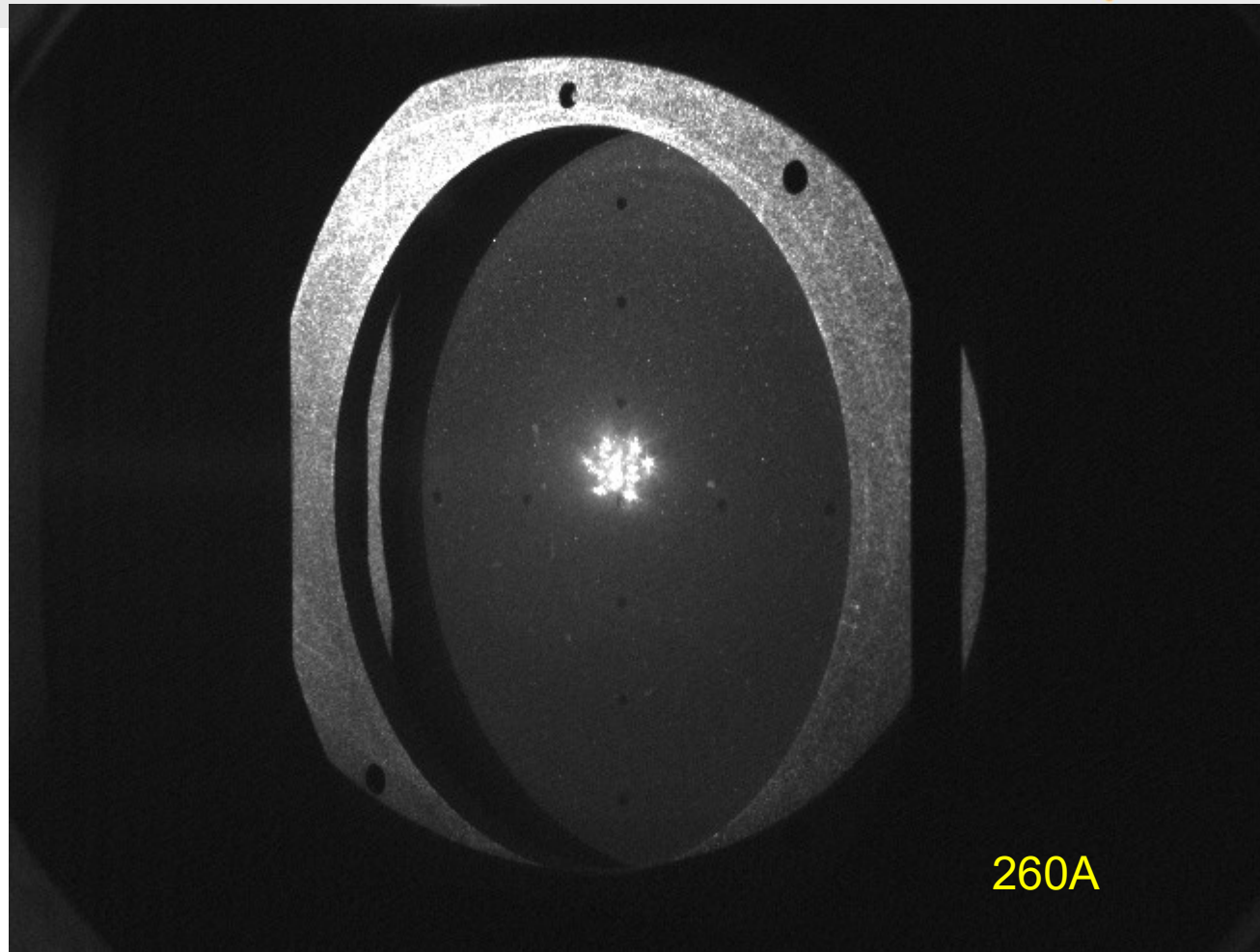
240A

Viewing Target



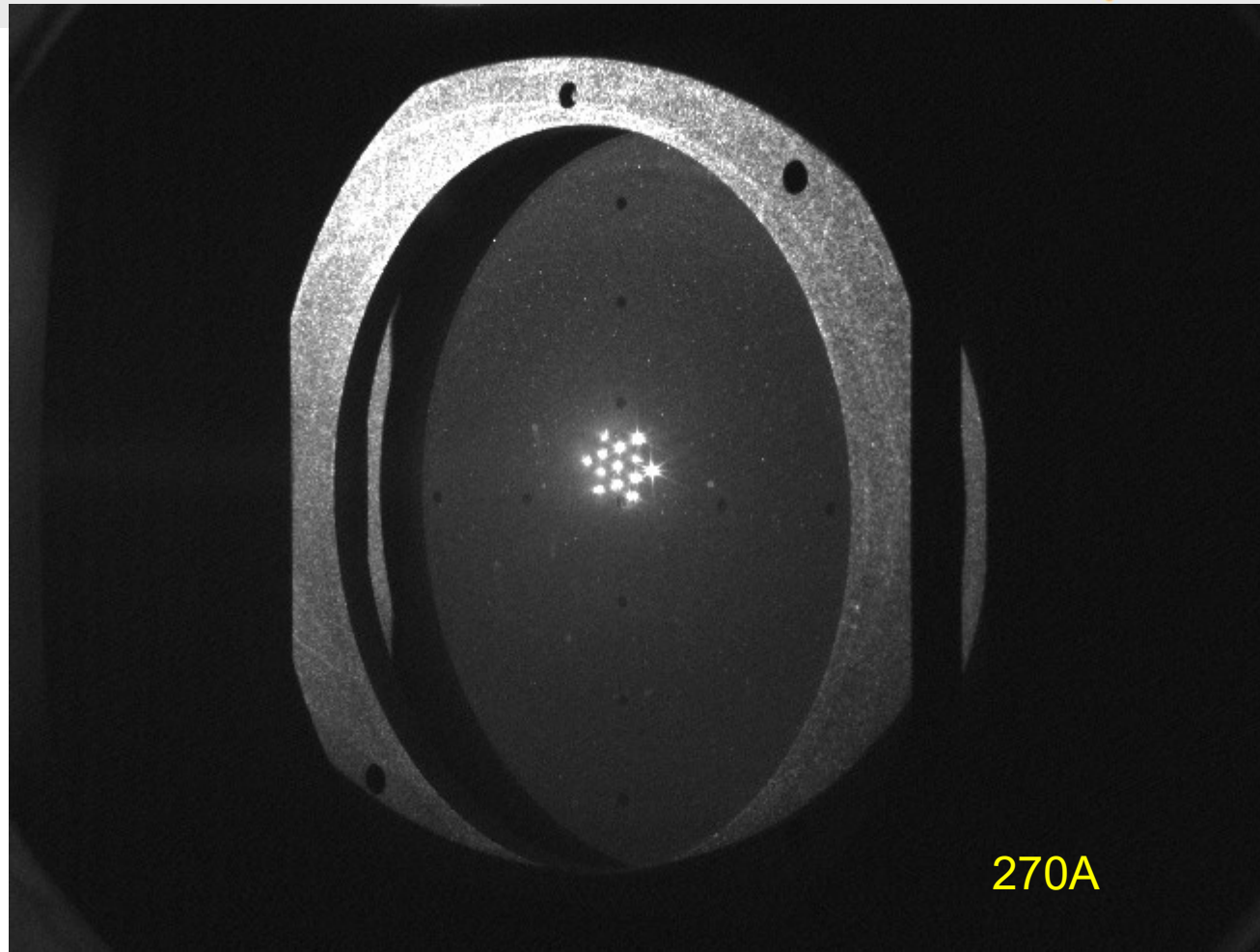
250A

Viewing Target

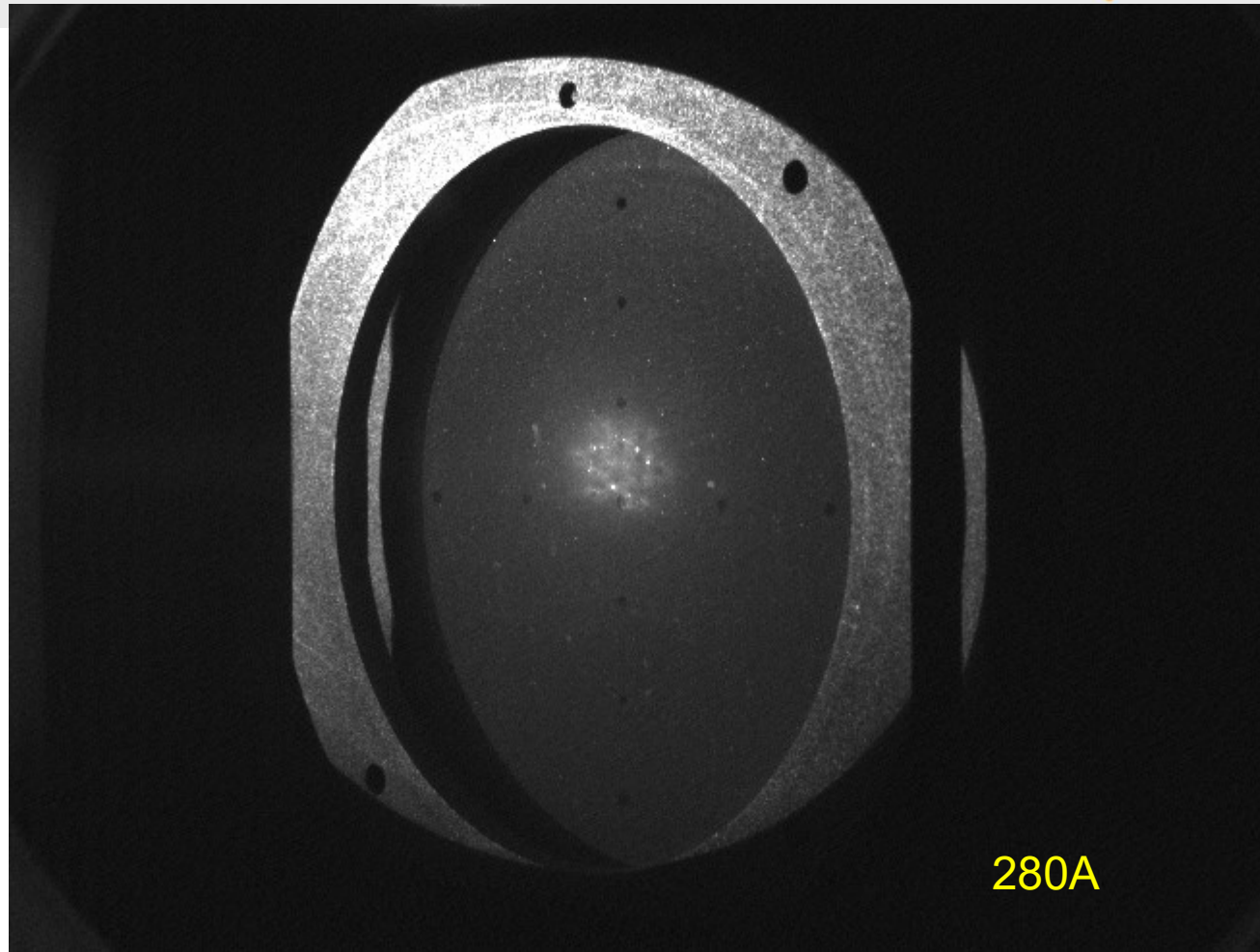


260A

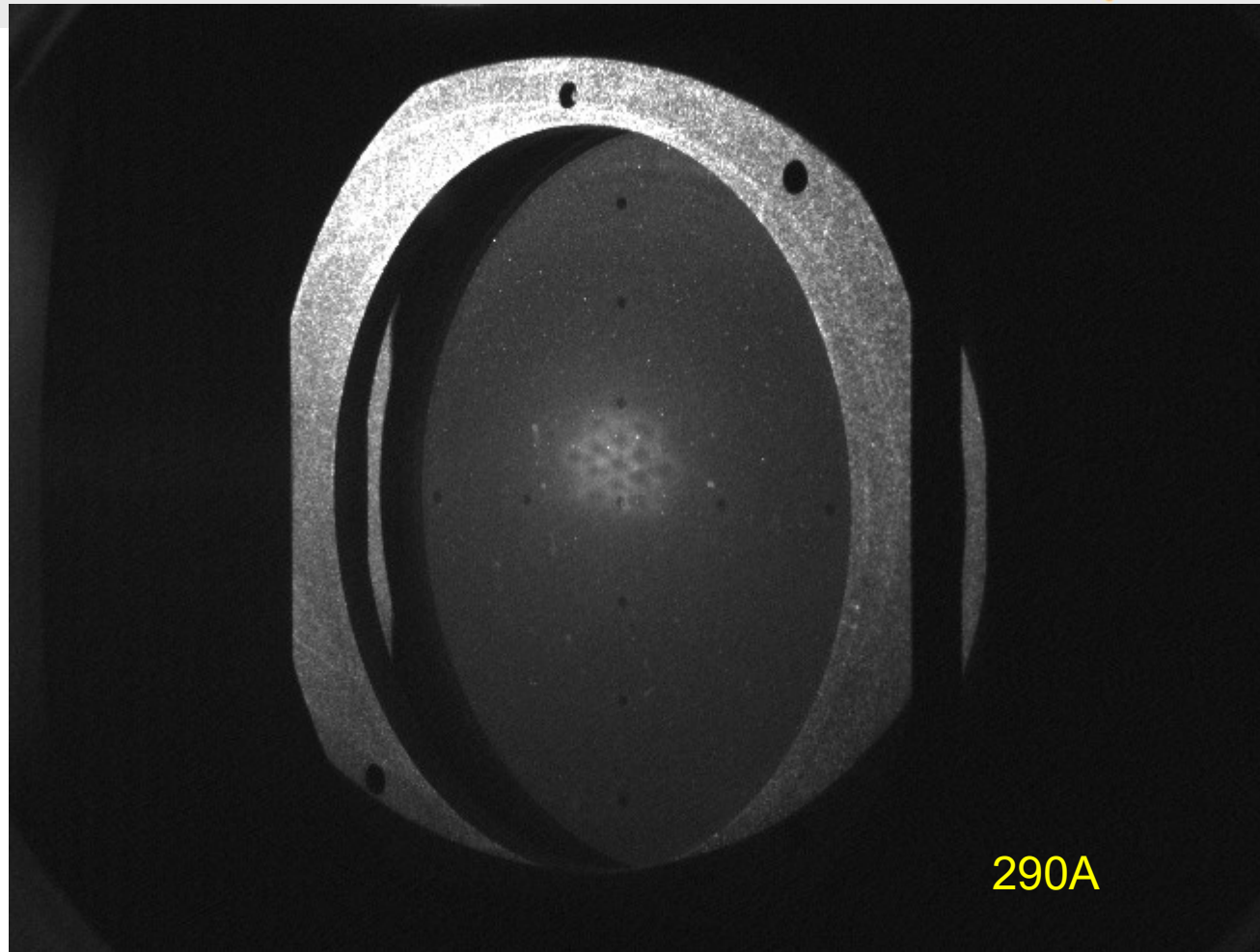
Viewing Target



Viewing Target

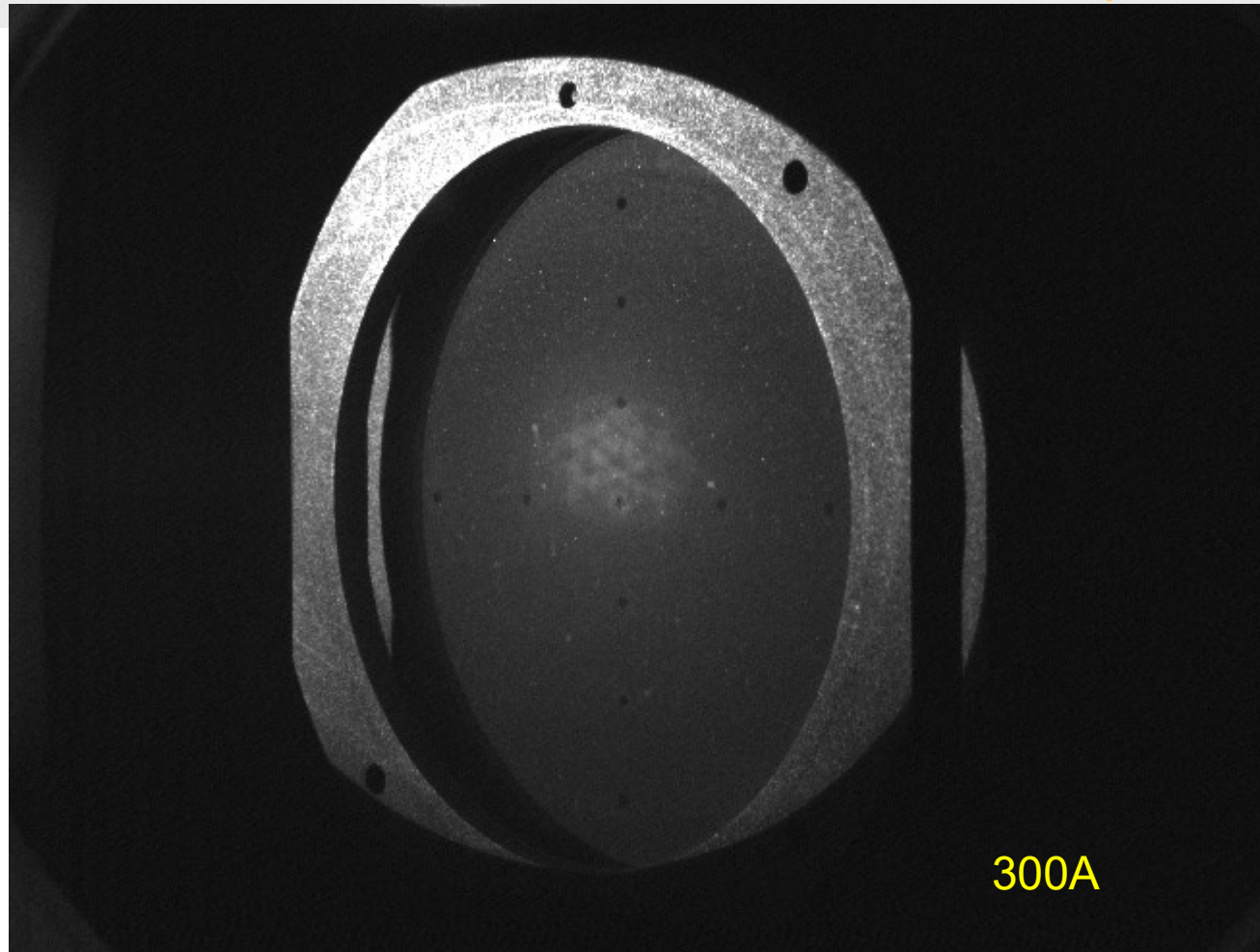


Viewing Target



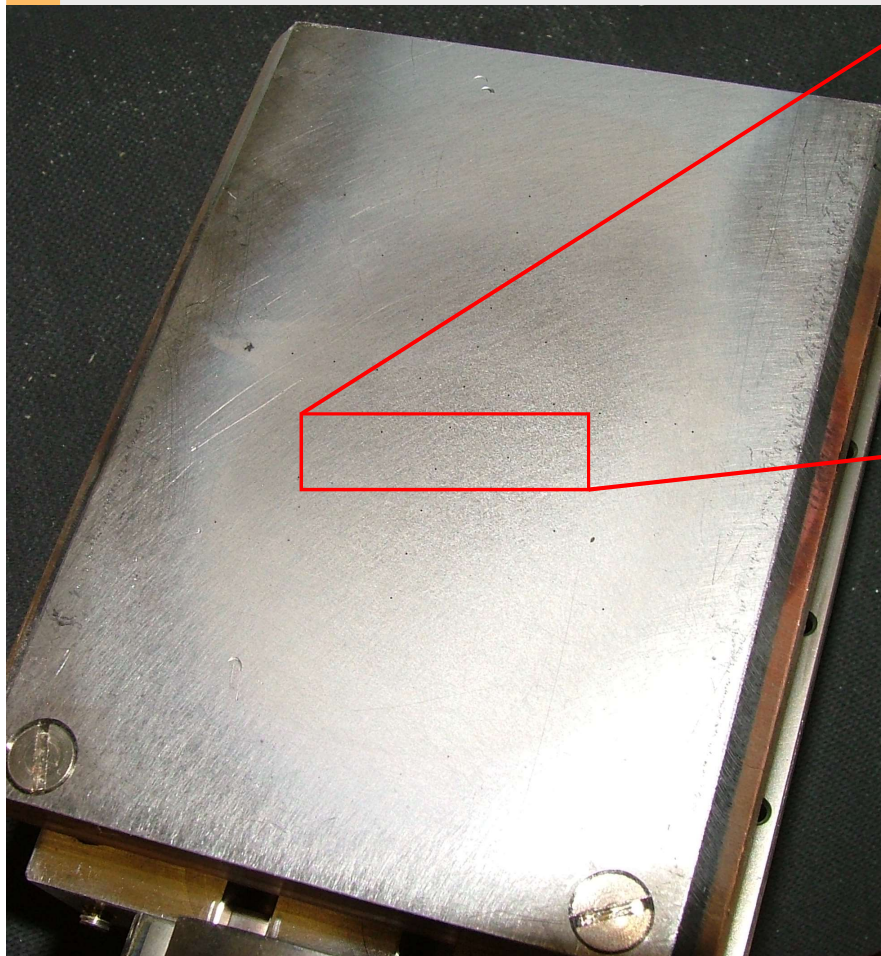
290A

Viewing Target

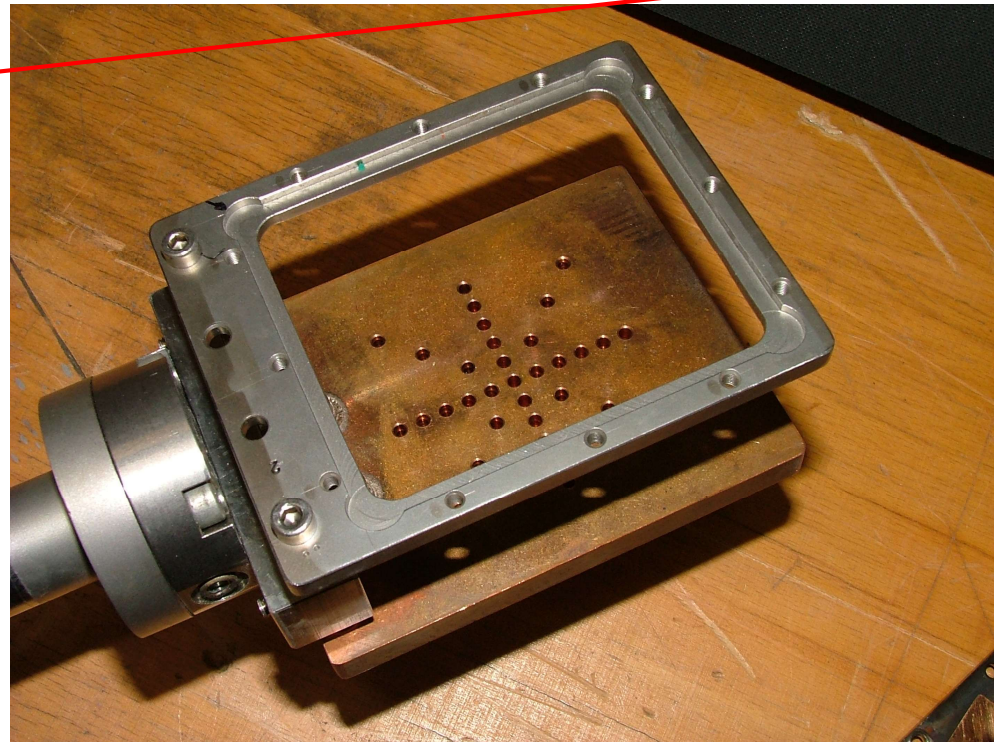


300A

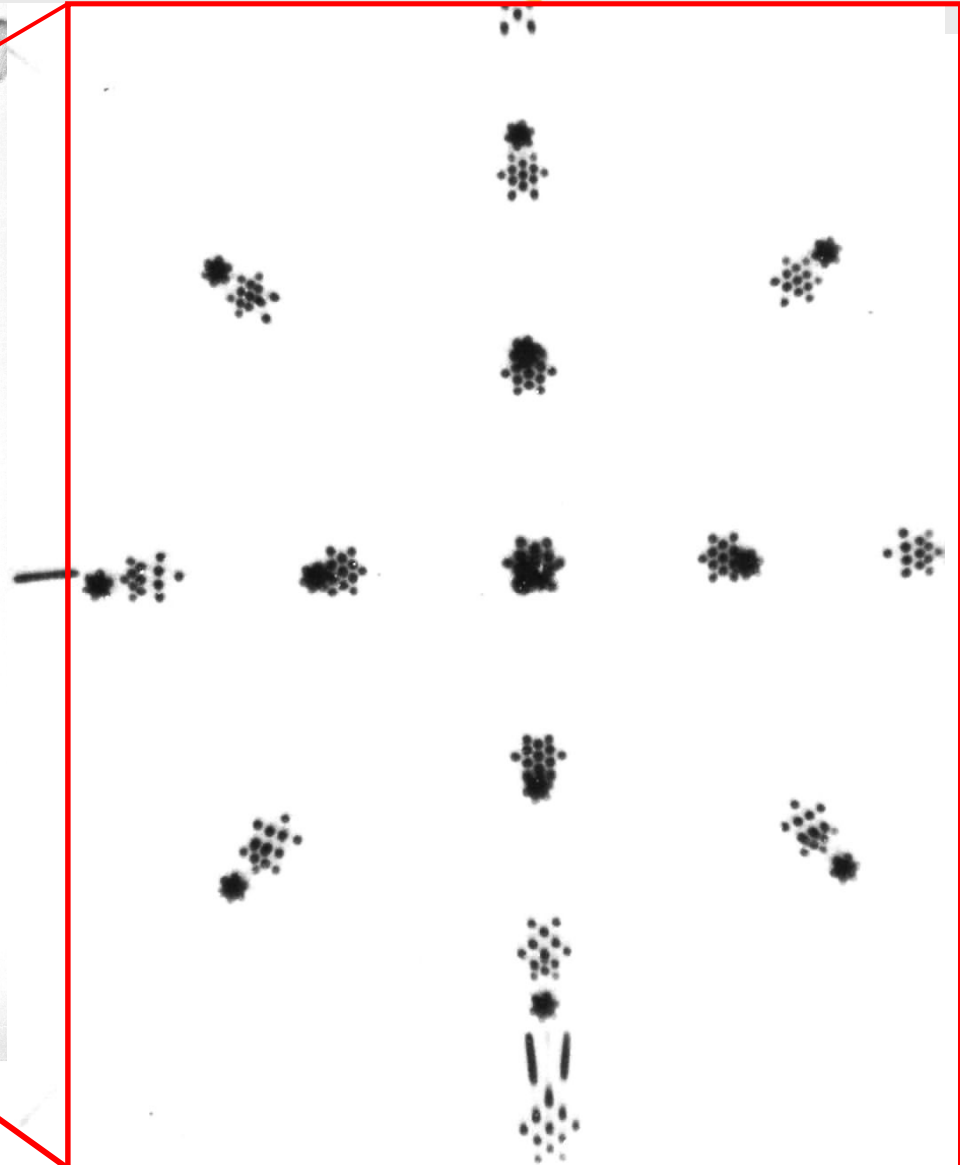
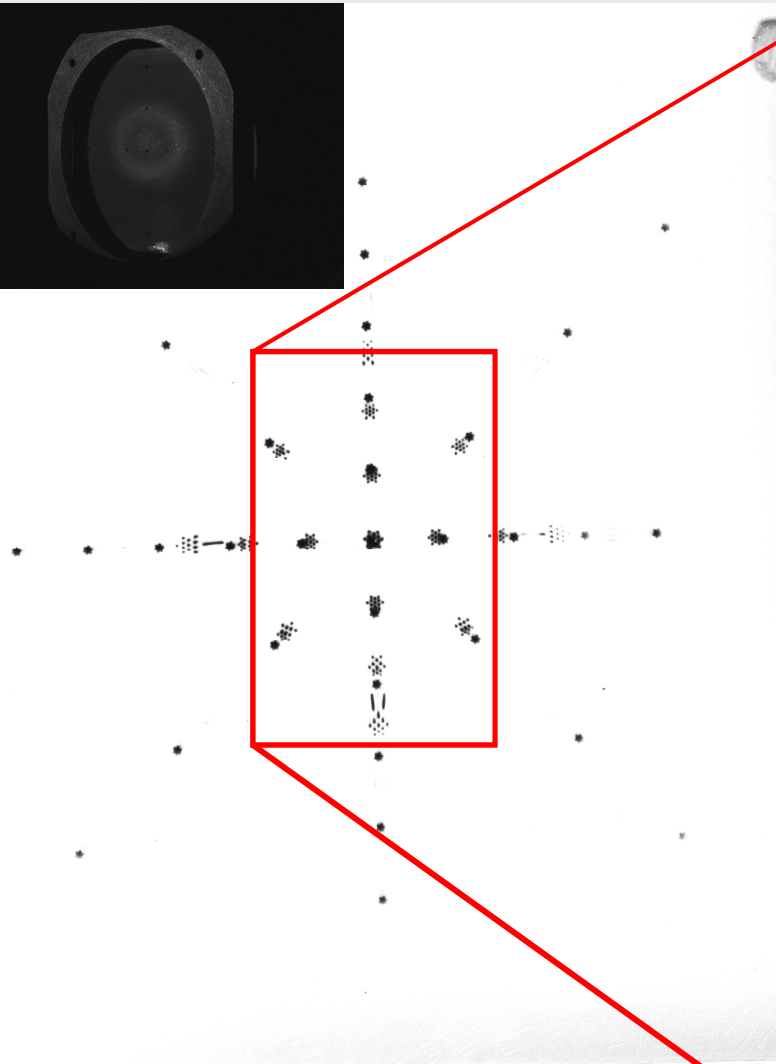
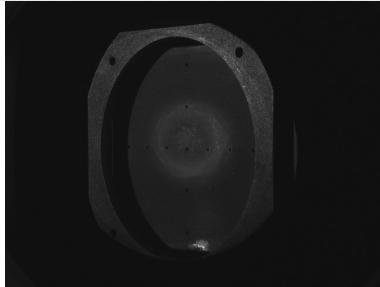
Pepper Pot



0.2 mm hole
5 mm distance



Pepper Pot for $I_{\text{sol}}=160\text{A}$



Pepper Pot, Ions bended by a Dipole

FAIR GSI

